

Injection synchrone de précurseurs liquides dans un plasma d'arc pulsé

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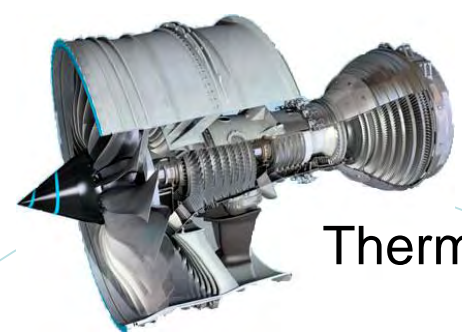
Limoges, France



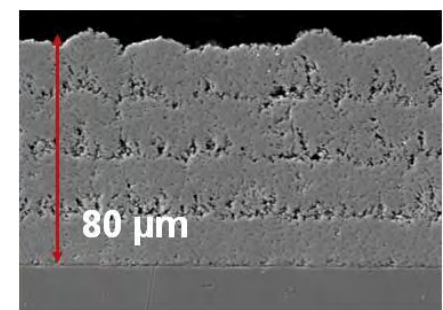
t_0 : janvier 2014
 Durée 24 mois
 33 keuros HT pour
 équipement injection

LIVRABLES	
Avant	<i>Modifications proposées</i>
Tâche 1 : Etude du plasma pulsé sans injection	
<ul style="list-style-type: none"> - Etude des instabilités de l'arc dans la torche résonante - Diagnostic du plasma sans injection 	<ul style="list-style-type: none"> - Etude de l'influence sur la stabilité de la torche de la superposition d'une variation de courant sinusoïdale à la composante continue du courant. (amplitude de courant variable faible par rapport à la composante continue). (mesure courant/tension et bilan énergétique sur torche) Suppression de l'étude acoustique. - Diagnostic spectroscopique <ul style="list-style-type: none"> • Identification des espèces et systèmes pour différentes distances et délai de déclenchement • Mesure de la température de rotation par simulation des spectres du premier système négatif de l'ion N_2^+ pour différentes distances et délais de déclenchement.
Tâche 2 : Etude du plasma pulsé avec injection synchrone	
<ul style="list-style-type: none"> - Mise en œuvre d'une injection piézo-électrique monobuse - Diagnostics (spectroscopie d'émission, émission acoustique) 	<ul style="list-style-type: none"> - Mise en œuvre d'une injection piézo-électrique monobuse - Identification des espèces et des systèmes pour différentes distances et délais de déclenchement. - Comparaison avec le cas sans injection Suppression de l'étude acoustique.
Tâche 3: Collecte/dépôt	
	<ul style="list-style-type: none"> - Collecte/dépôt en point fixe et rotation (formation de cordons) – mise en place cinématique dépôt - Corrélation entre microstructure/structure et distances/délais de déclenchement (analyse MEB, DRX et optique)

Plasma spraying of liquid feedstock (suspensions/solutions)



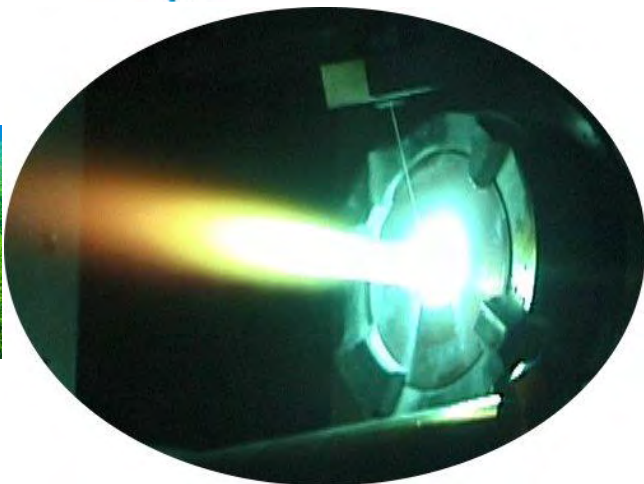
Thermal barrier coatings



Control of coating microstructures, structures, chemical composition



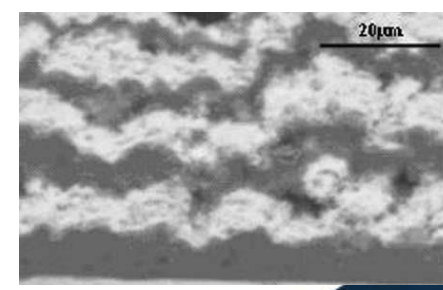
Photocatalytic coatings



Biomaterials



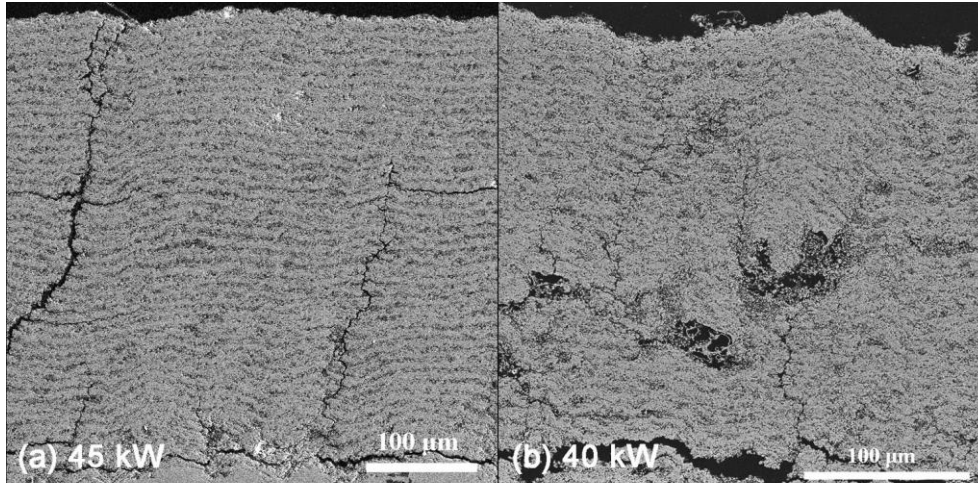
Wear resistance



O. Tingaud *et al.*,
J. Thermal Spray Technol. (2010)

Coating properties depend on plasma jet stability :

Dependence of in-flight processes affecting liquid and submicron powders



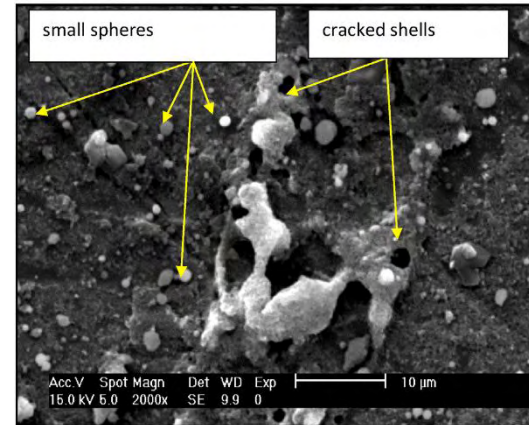
Thermal Barrier Coatings
YSZ deposition by Solution Precursor
Plasma Spraying SPPS
Jordan et al. , J. Thermal Spray Technol.
16, 2014

Thermal decomposition of perovskites

Suspension pérovskite LaMnO_3



C. Monterrubio-Badillo et al., Surf. Coat. Technol. (200), 2006.

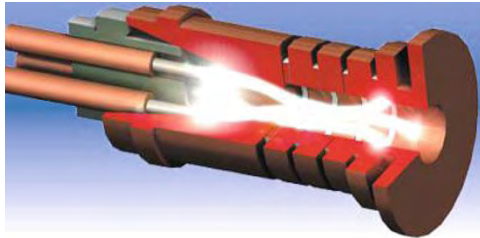


HA coatings for biomaterials
SPPS deposition

R. Candidato et al., Surf. Coat. Technol. (277), 2015.

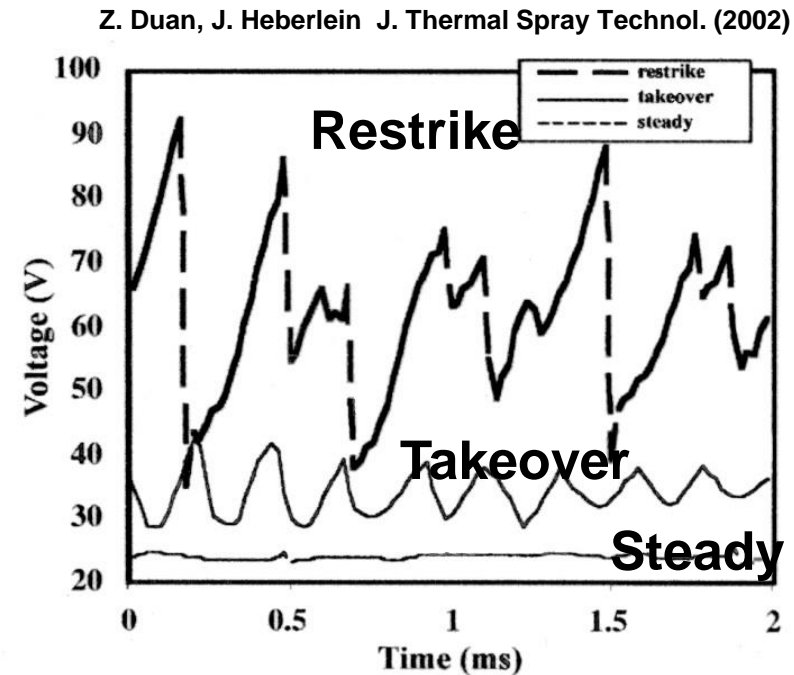
- ◆ Problem of arc instabilities in dc torches
 - Different modes of arc instabilities
 - Each torch geometry has its own signature
 - Difficult to predict

- ◆ How to stabilize the arc ?
 - ⇒ Cascaded dc torches

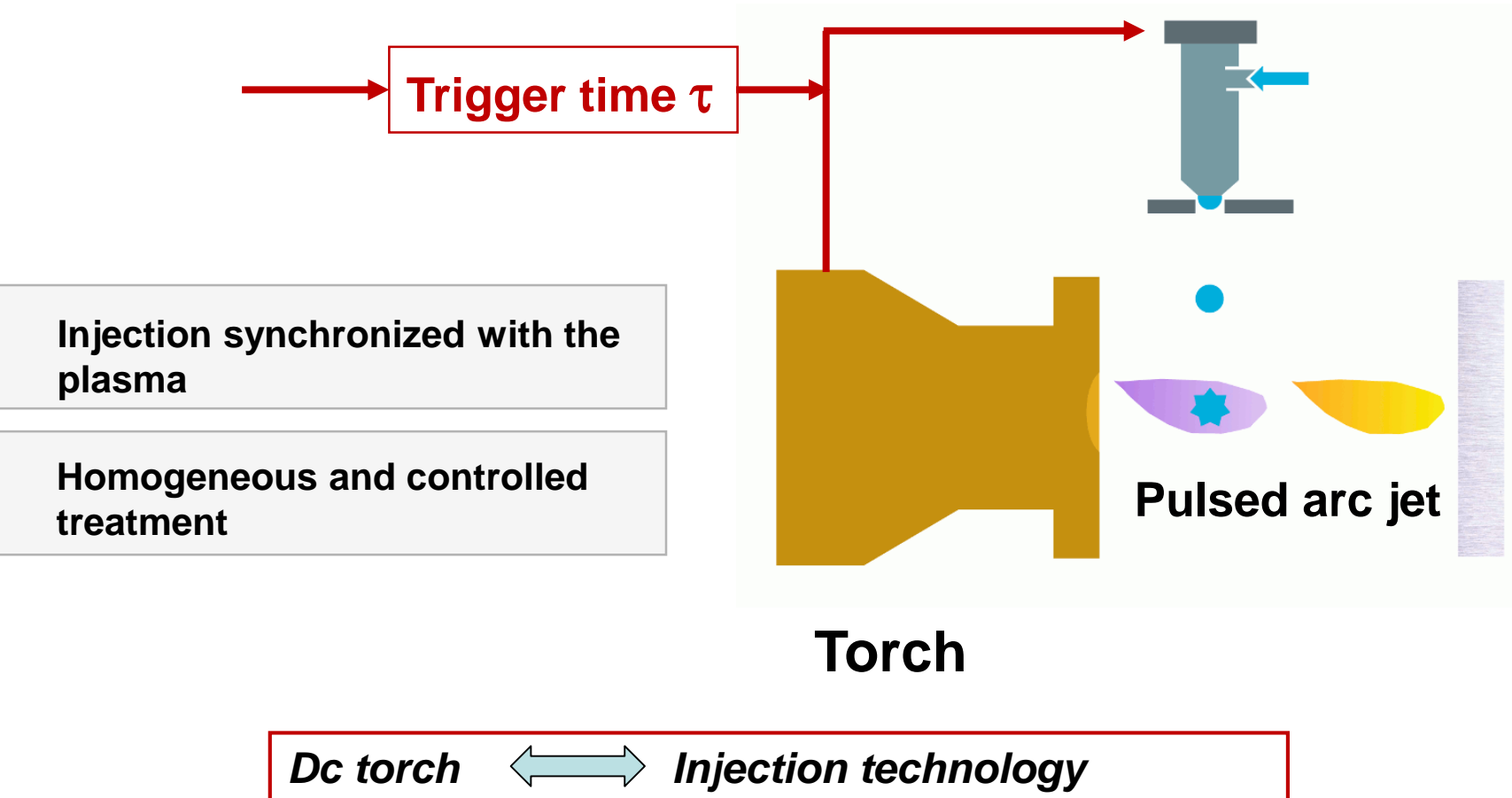


How to control the arc to improve heat and momentum transfers ?

⇒ Pulsed plasma jet with a synchronized drop-on demand injection of droplets



Basic idea of pulsed plasma spraying with synchronized injection of droplets

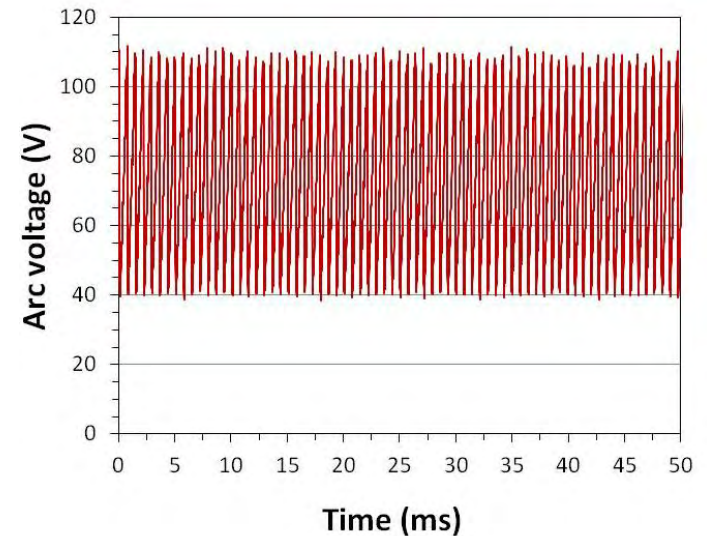
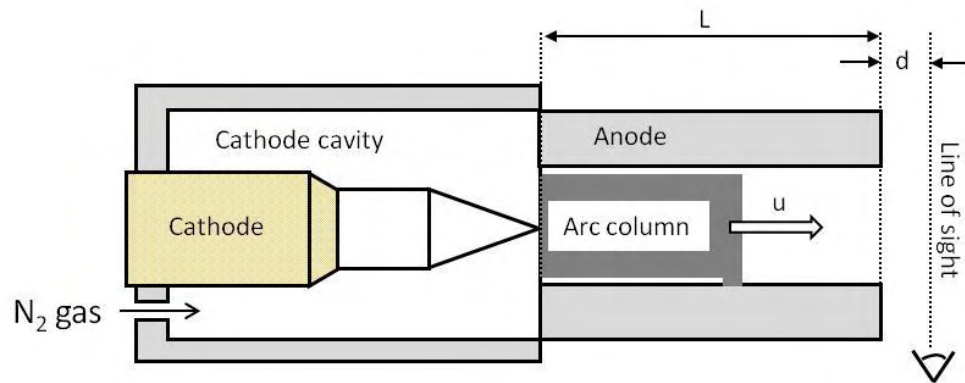


OUTLINE

- 1- Direct current pulsed arc: restrike mode, properties
- 2- Modulation of arc current
 - stabilizing the pulsed mode
 - dynamics of the arc
- 3- Plasma spraying of solution precursor in pulsed mode
 - liquid injection
 - dependence of in-flight processes on injection timing
 - coating features

Self-sustained pulsed arc

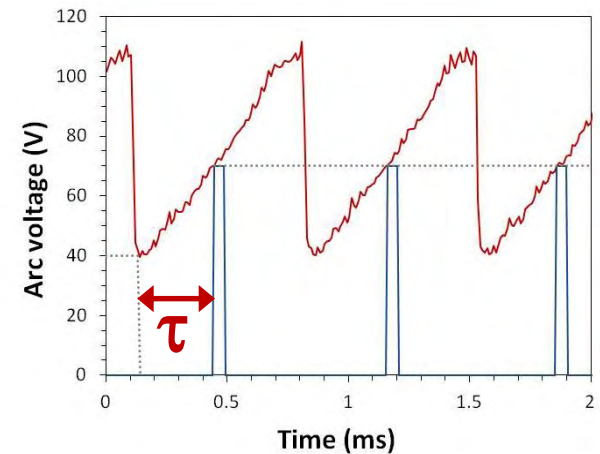
➤ Direct Current $I = 15\text{ A}$ – N_2 – Atmospheric pressure



◆ Natural frequency of the torch:
 $f_m \sim 1.4\text{ kHz}$

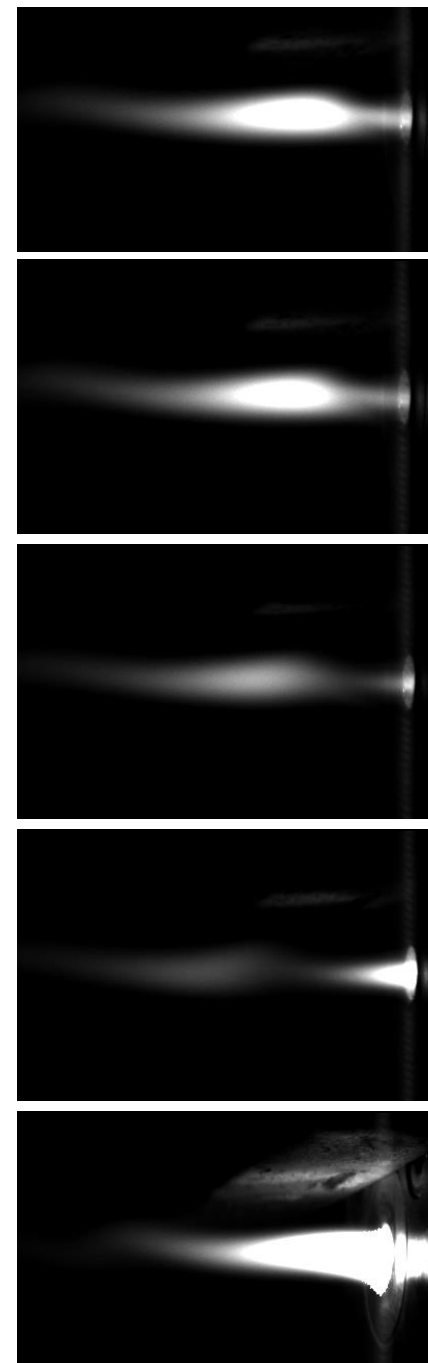
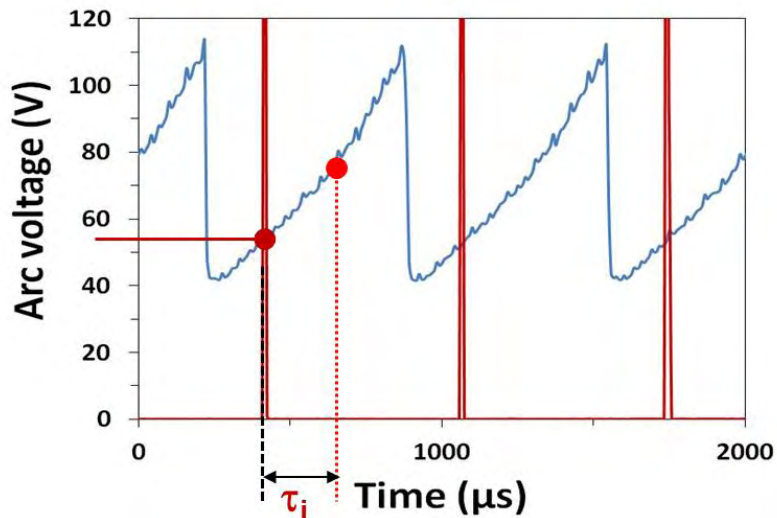
◆ $h_{\text{moy}} = 13\text{ MJ.kg}^{-1}$

◆ Pulsed mode: Restrike mode promoted



➤ Trigger time τ_i

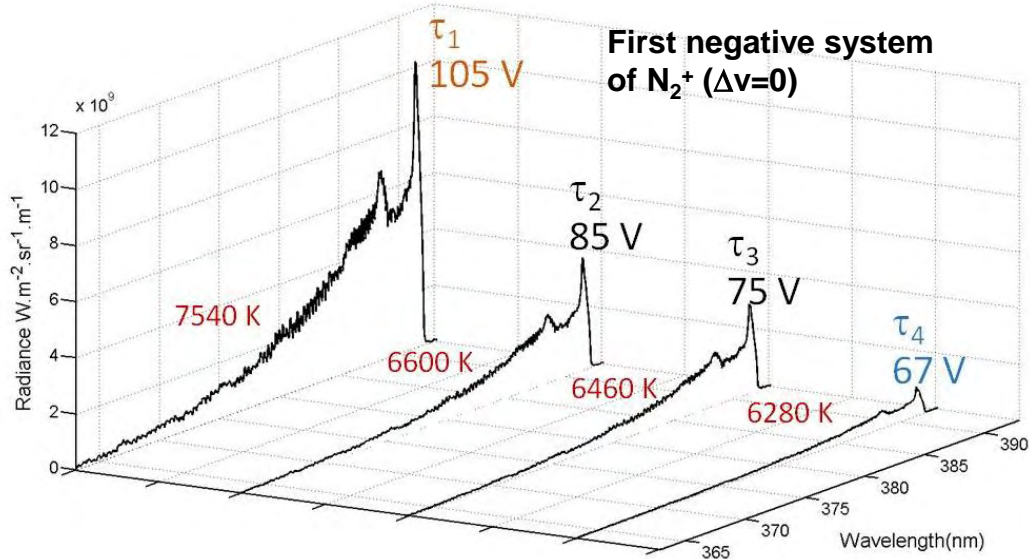
Laminar pulsed arc jet



Time aperture
 $60 \mu\text{s}$

Period
 $T_m = 700 \mu\text{s}$

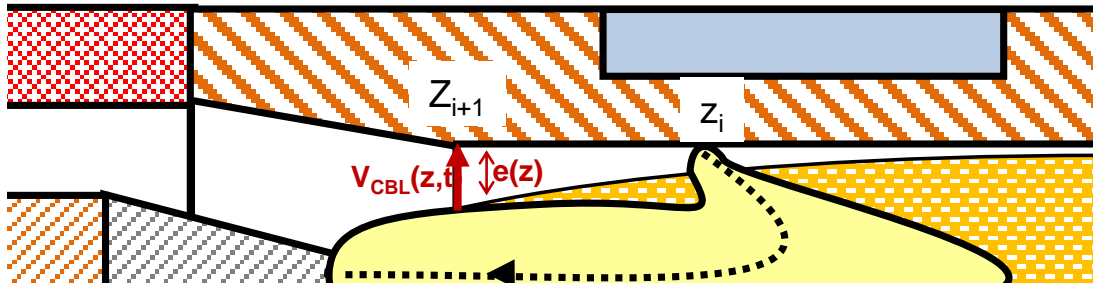
Time-resolved temperature measurements



Influence of arc current modulation

- ◆ Motivations : increase the life time of pulsed mode to satisfy plasma spraying conditions
- ◆ How to influence the restrike mode ?
 - ⇒ arc current influences the arc reattachment through boundary layer in the arc channel
 - ⇒ restrike model

Breakdown voltage V_b



Rearcing in $z = z_{i+1}$ if $V_{\text{CBL}}(z_{i+1}, t) \geq V_c$ $V_c = e_{\text{CBL}}(z_{i+1}, t_i) \bar{E}_c$

$$V_{\text{CBL}}(z_{i+1}, t_i) = V_{\text{col}}(z_i, t_i) - V_{\text{col}}(z_{i+1}, t_i) + V_\ell(z_i, t_i) + U_a$$

⇒ Criterion for restrike :

$$(z_i - z_{i+1}) E_{\text{col}}(t_i) + U_a \geq (r_0 - r_{\text{arc}}(t_i)) \bar{E}_c$$

⇒ Restrike depends on arc radius and the electric field strength

Expected influence of arc current modulation on restrike

- Electric field strength
- Boundary layer thickness

$$I(t) = 2\pi E_{\text{col}}(t) \int_0^{r_{\text{arc}}} r \sigma(r, t) dr$$

Characteristic frequency for heat transfer f_{th} in the arc column is higher than the excitation frequency $f_{\text{th}} > f_0$

- Magnetic forces

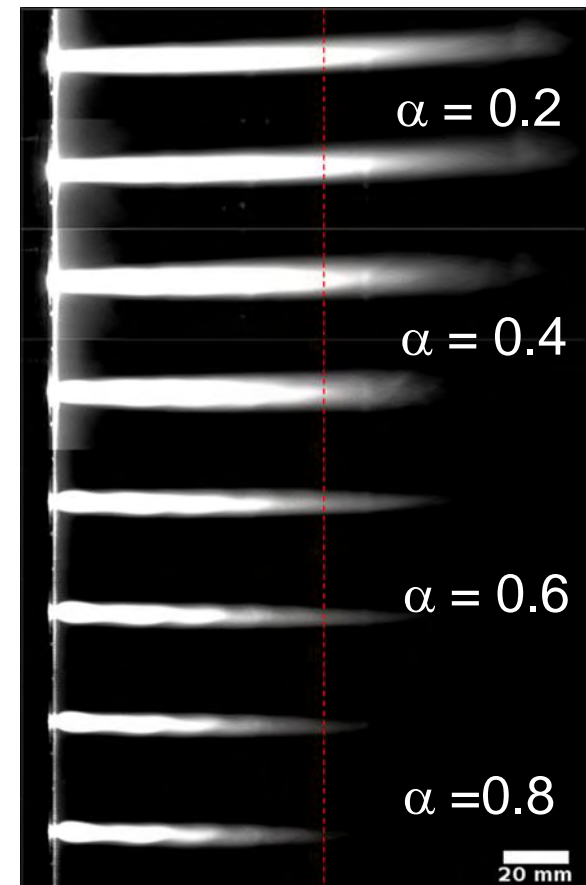
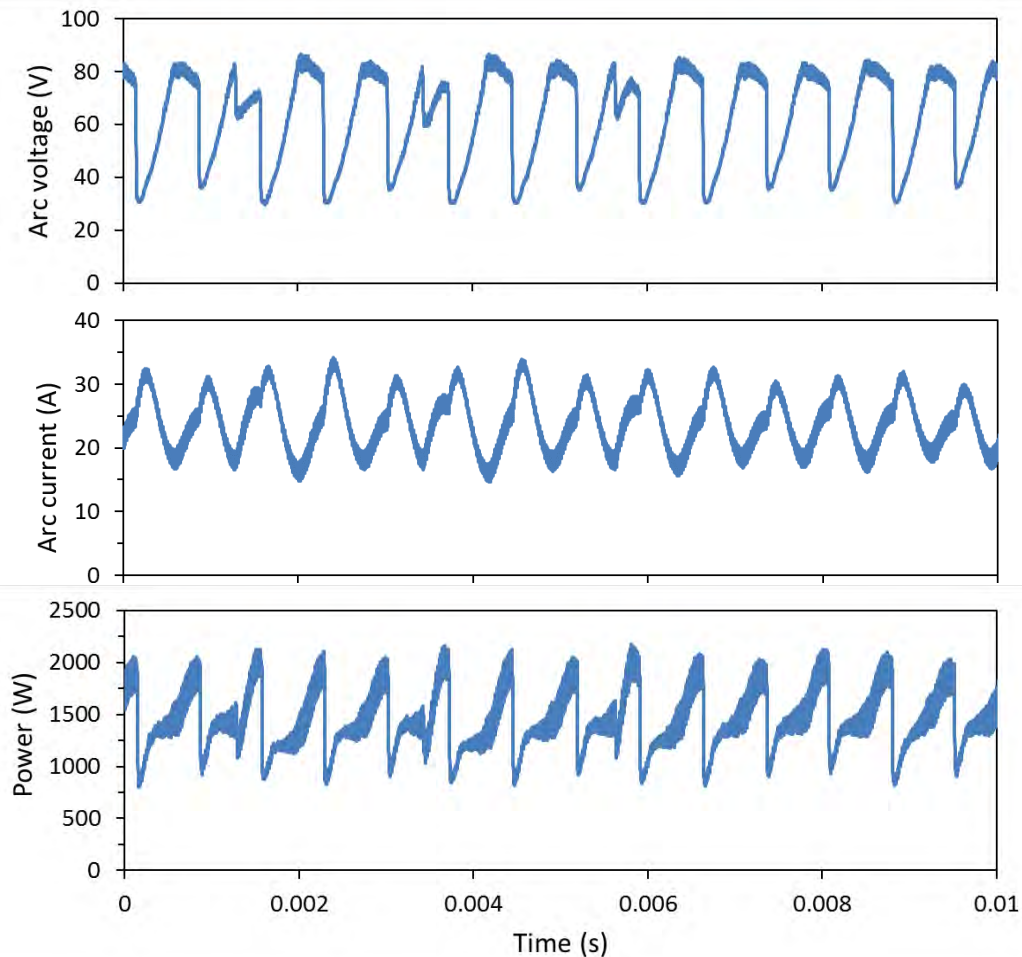
- *What kind of current modulation ?*

$$I(t) = I_0 (1 + \alpha \sin(2\pi f_0 t))$$

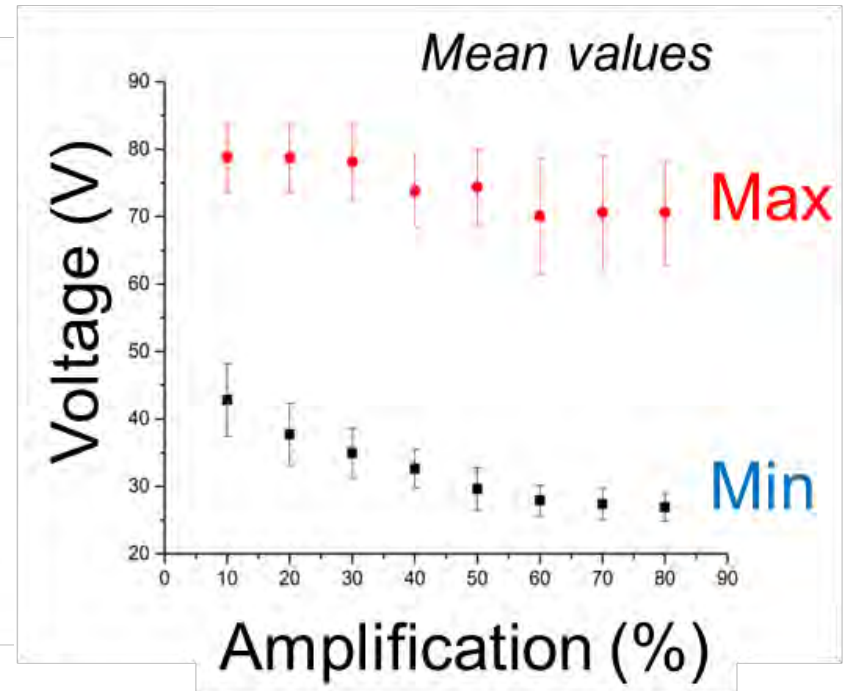
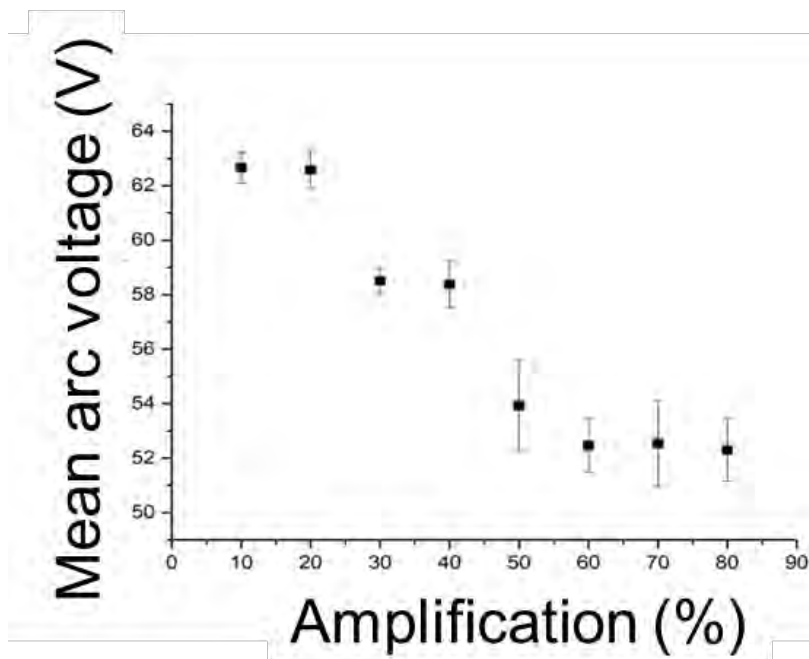
- α : amplification coefficient (< 1)
- f_0 : excitation frequency close the natural frequency f_m

Typical signals

$I_0 = 25 \text{ A}$, $\alpha = 0.4$ and $f_0 = f_m = 1.4 \text{ kHz}$

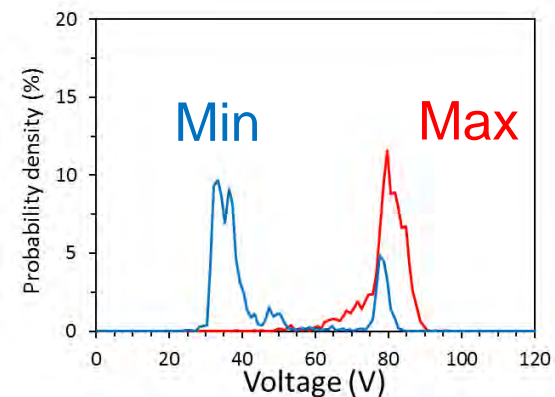
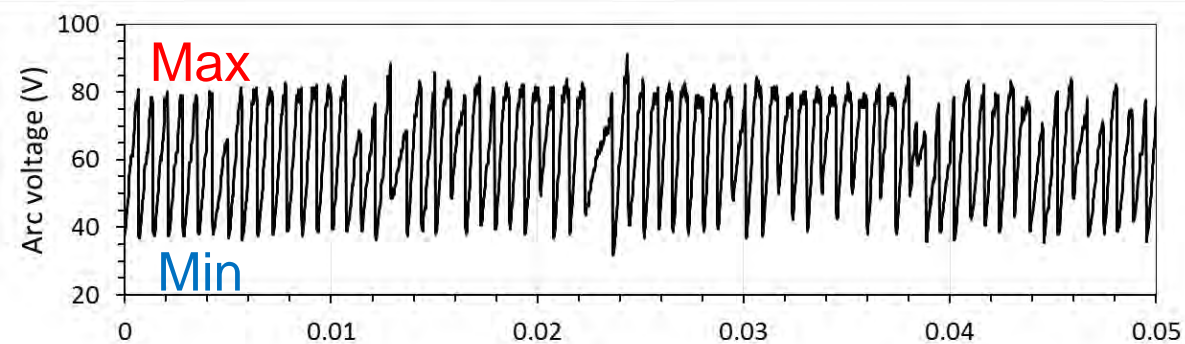


Influence of amplification coefficient α - $f_0 = f_m$

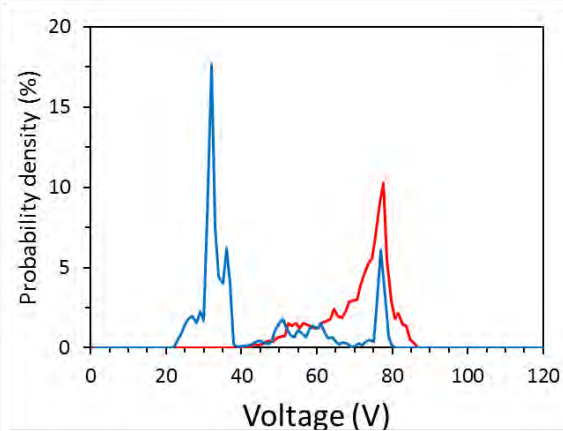
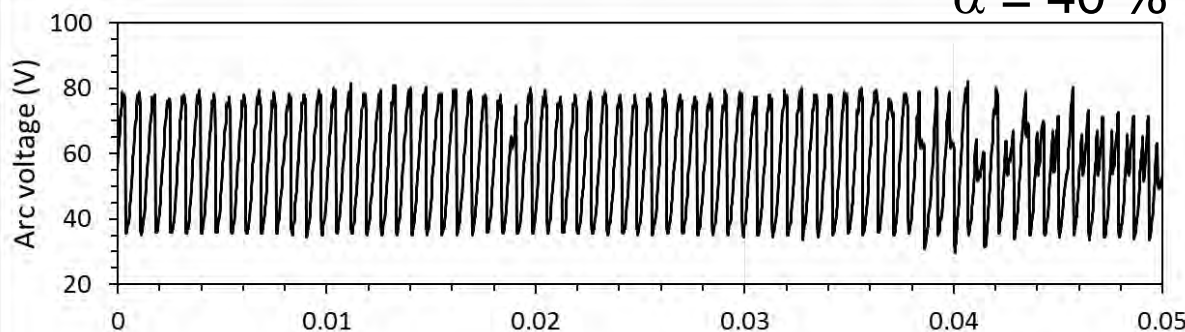


N=4000-6000 samples

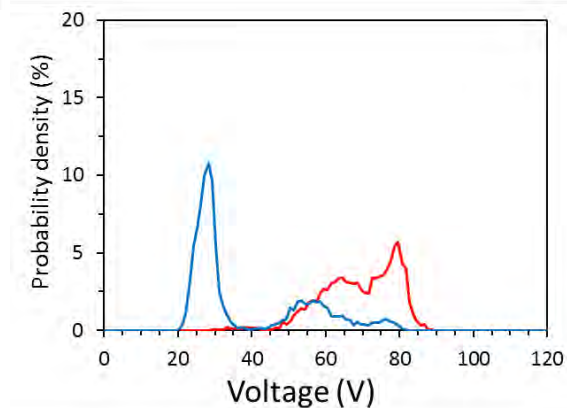
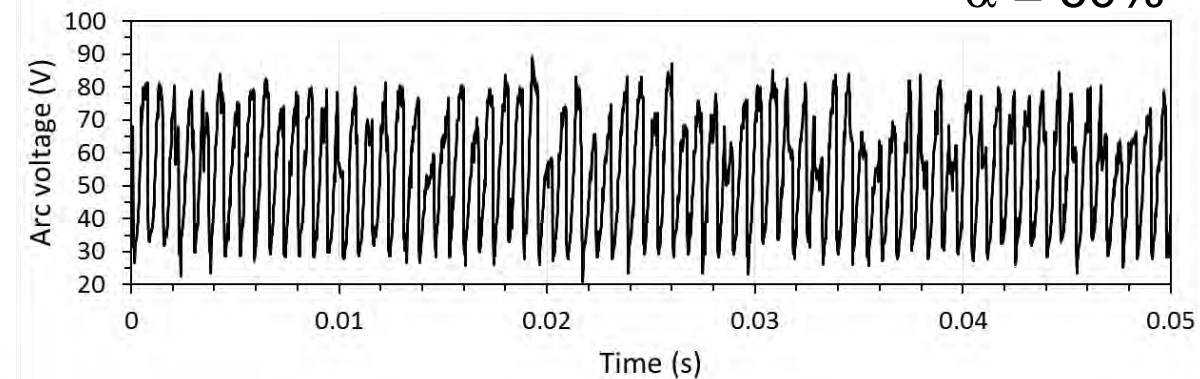
$\alpha = 20 \%$



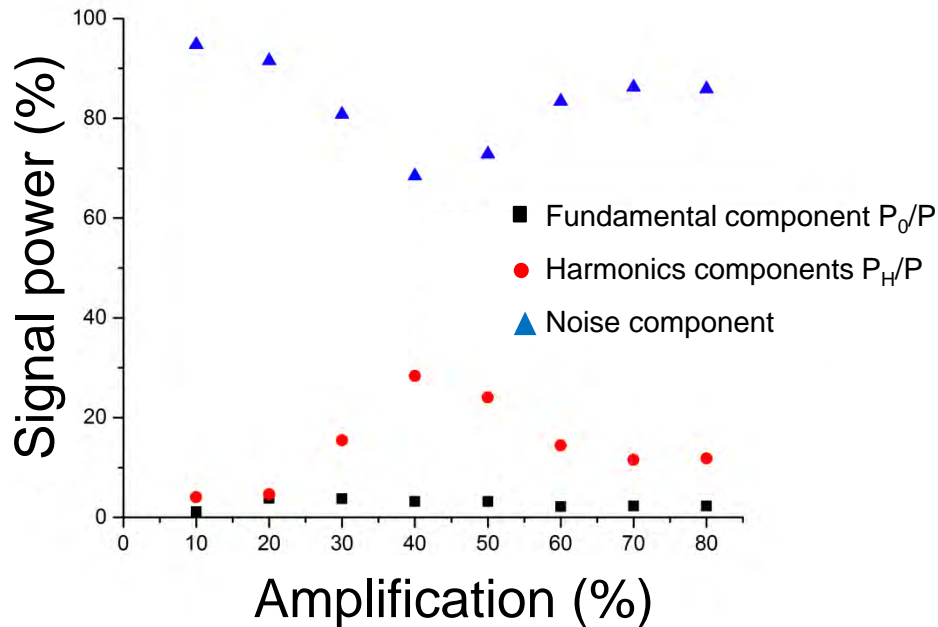
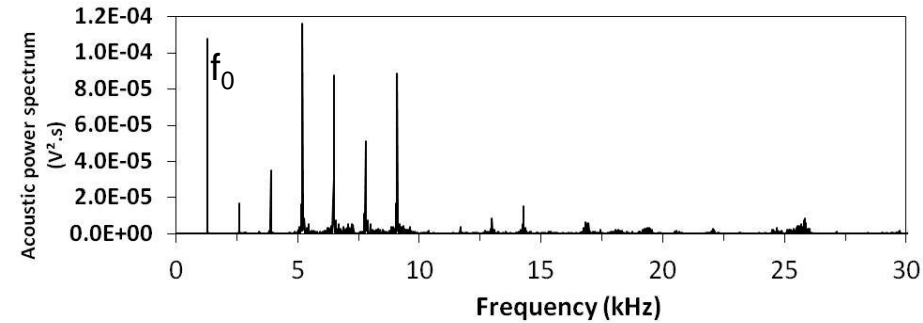
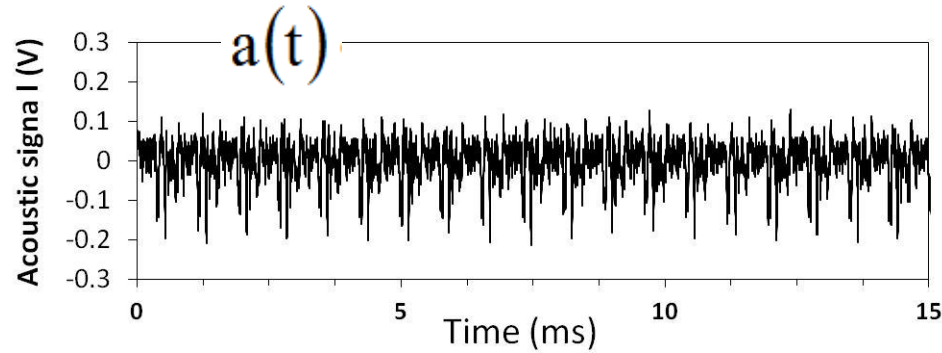
$\alpha = 40 \%$



$\alpha = 60 \%$



Acoustic study



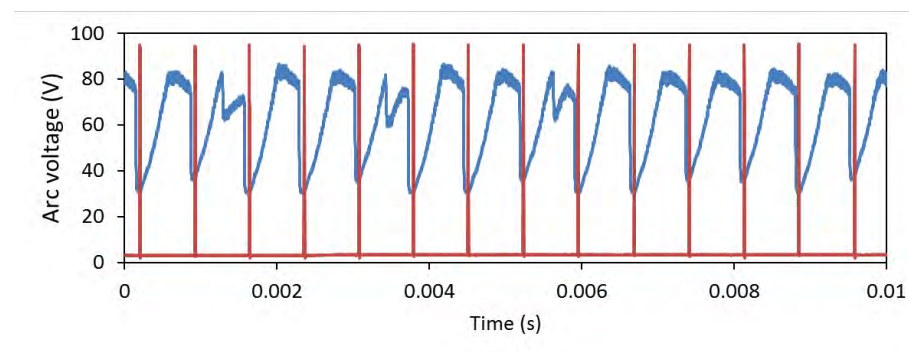
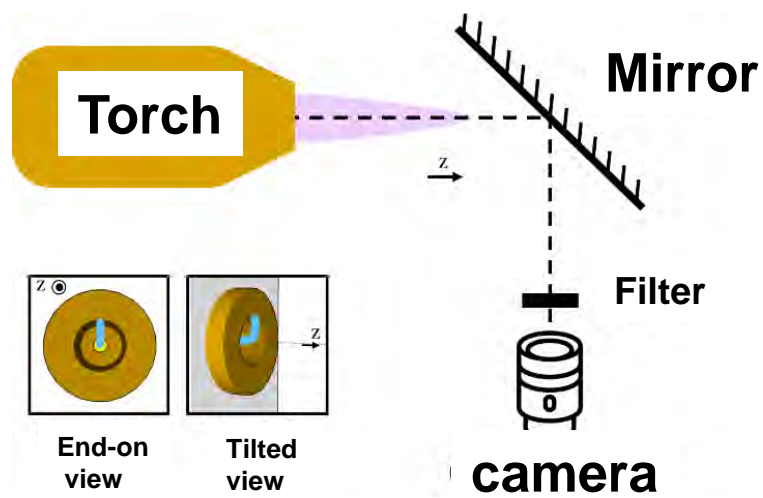
Acoustic emission: Fitaire law

$$a(t) \propto \frac{dP_{elec}}{dt}$$

- Reduction of noise
- Stabilizing effect of arc current on restrike

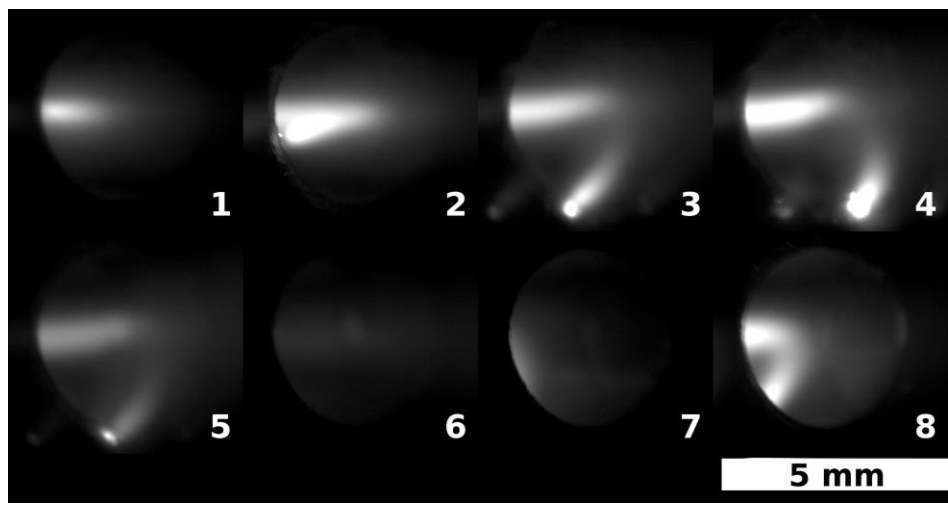
Dynamics of the arc

Time-resolved end-on imaging of the arc channel – $\alpha = 0.4$ - $f_0 = 1.4\text{kHz}$

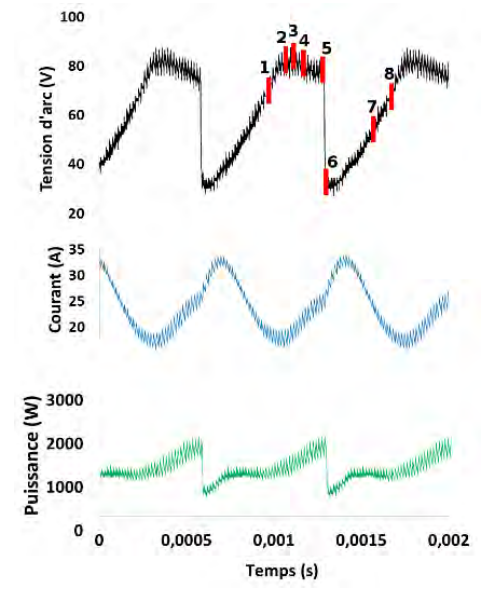


➤ Trigger time τ

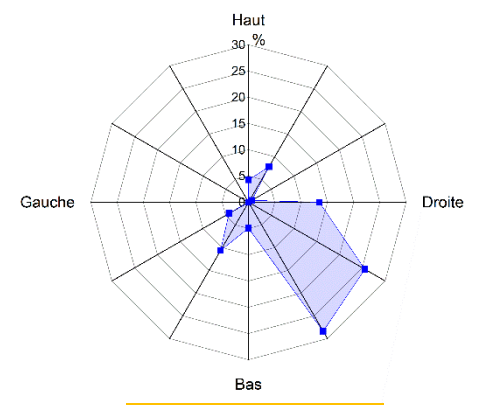
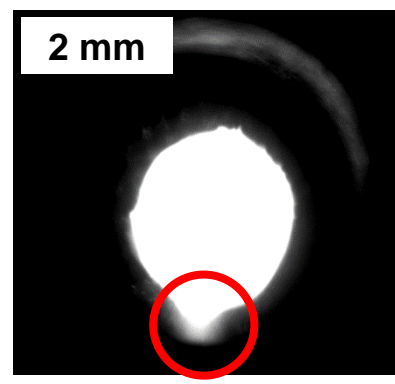
Arc dynamics : single restrike



Time-resolved imaging, exposure time 50 μ s

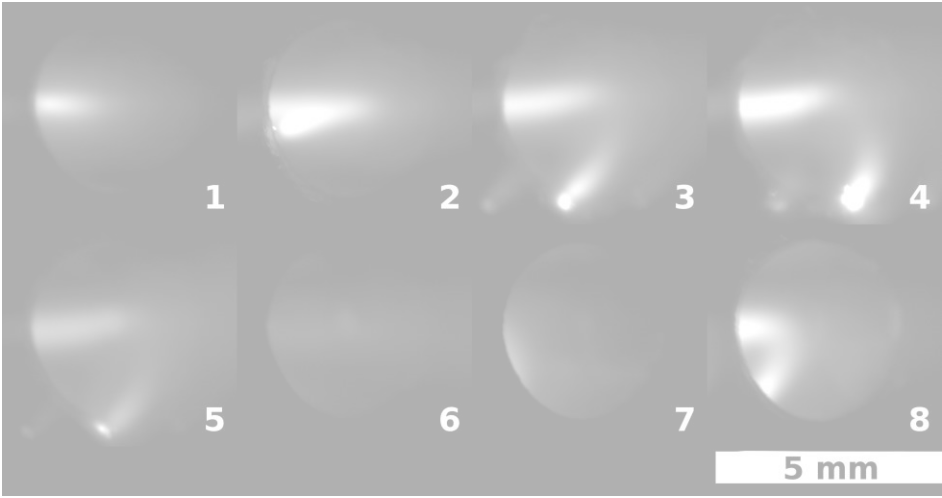


Distribution of arc root positions

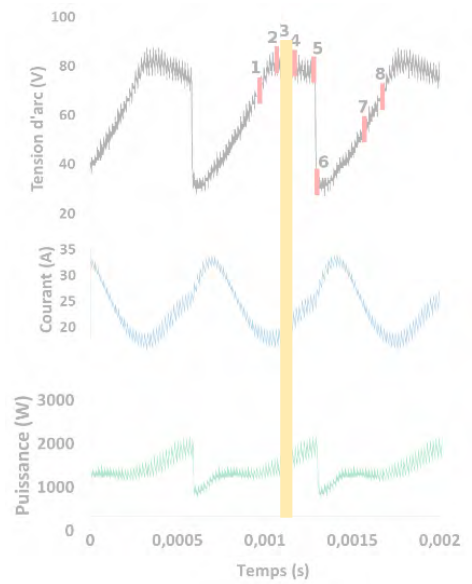


Before rearing

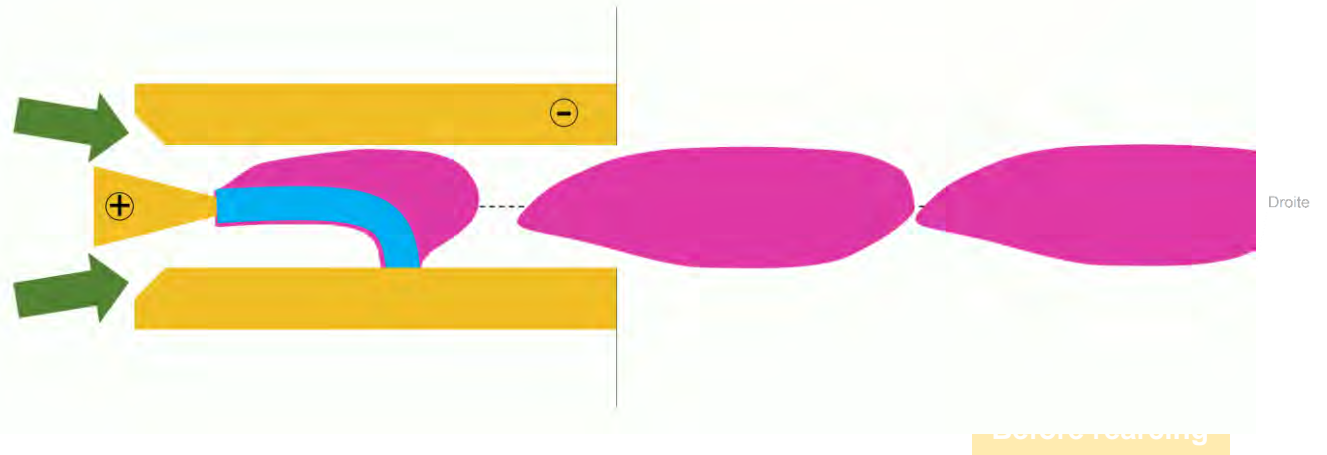
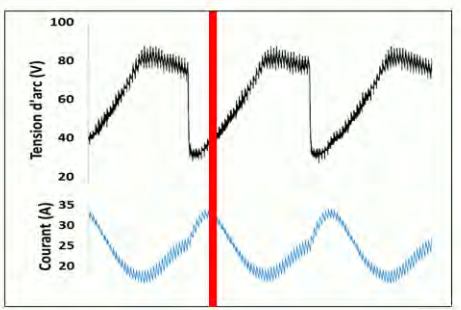
Arc dynamics : single restrike



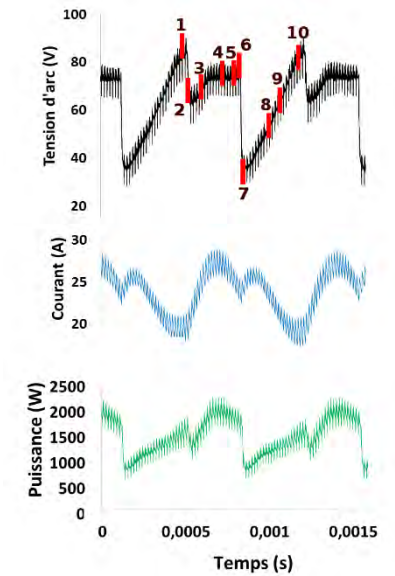
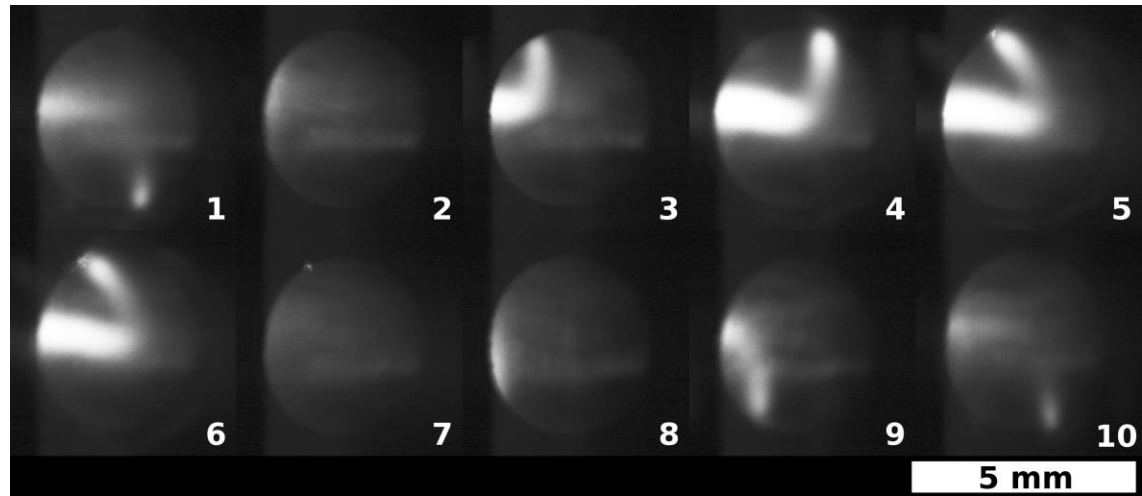
Time-resolved imaging, exposure time 50 μ s



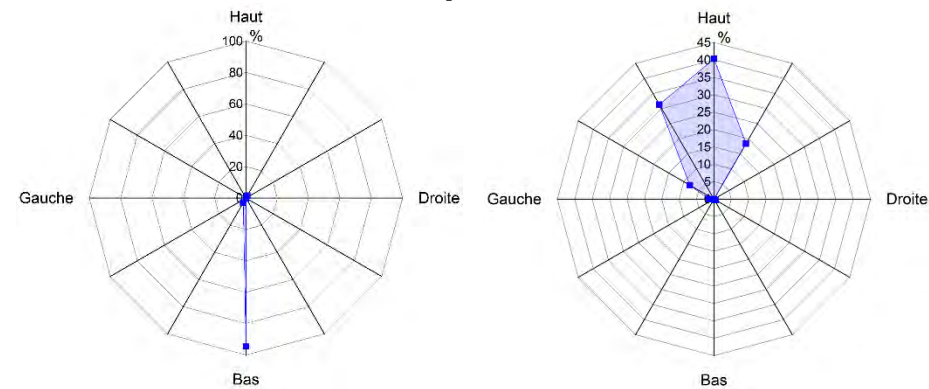
Distribution of arc root positions



Arc dynamics : double restrike



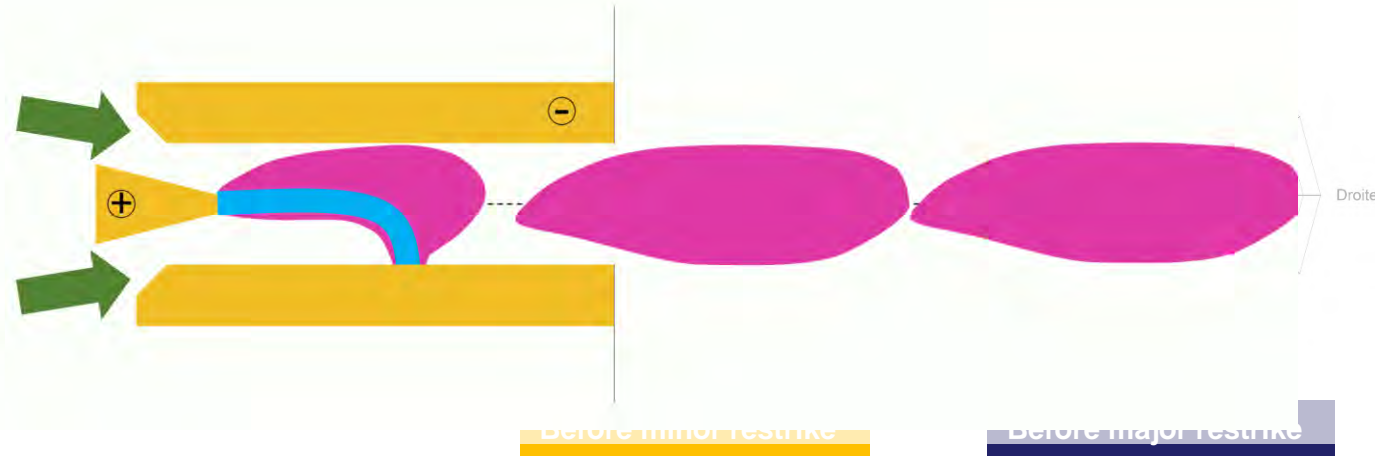
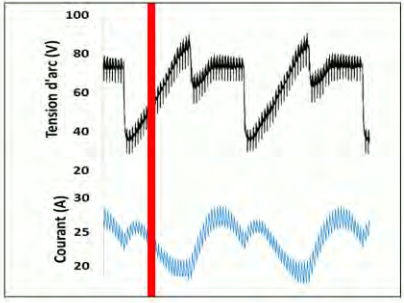
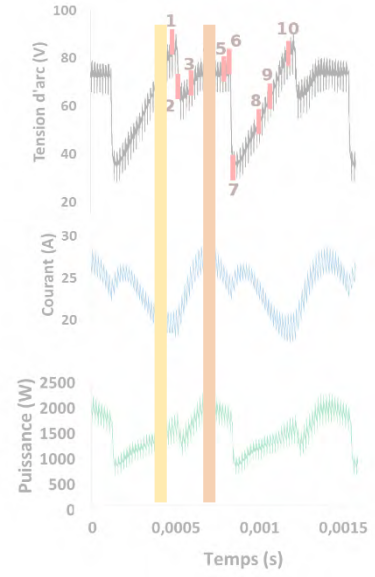
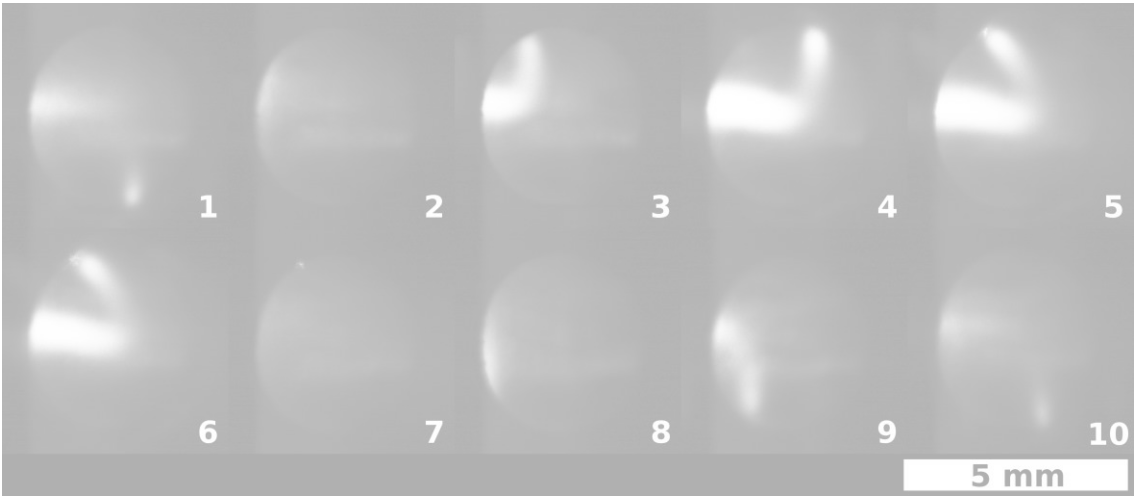
Distribution of arc root positions



Before minor restrike

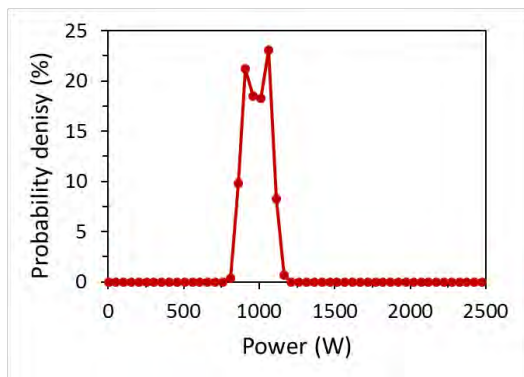
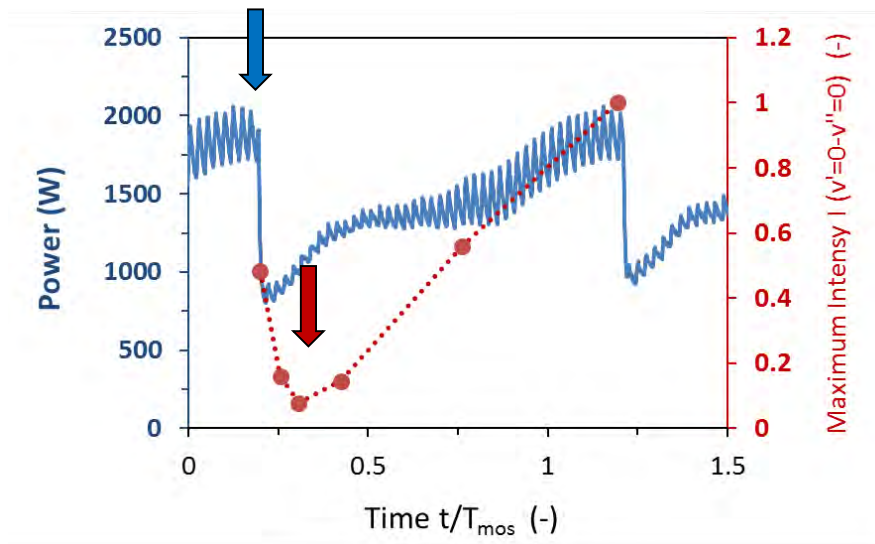
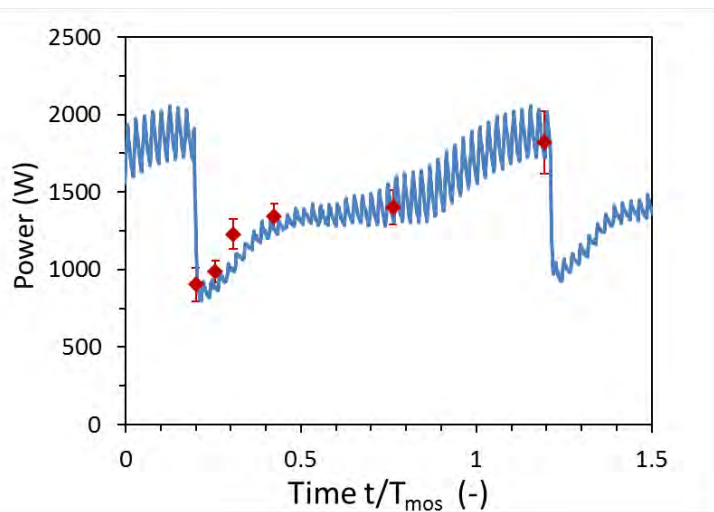
Before major restrike

Arc dynamics : double restrike

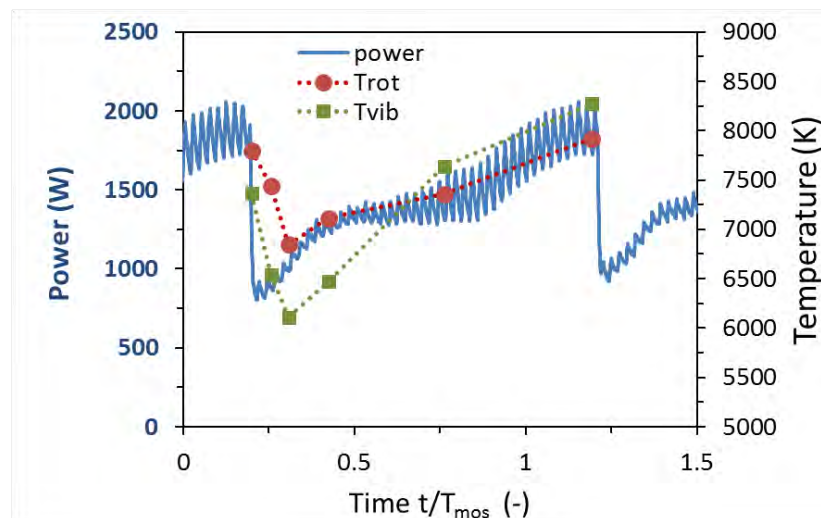


Time-resolved temperature measurements ($z = 1 \text{ mm}$) $\alpha = 0.4 - f_0 = 1.4\text{kHz}$

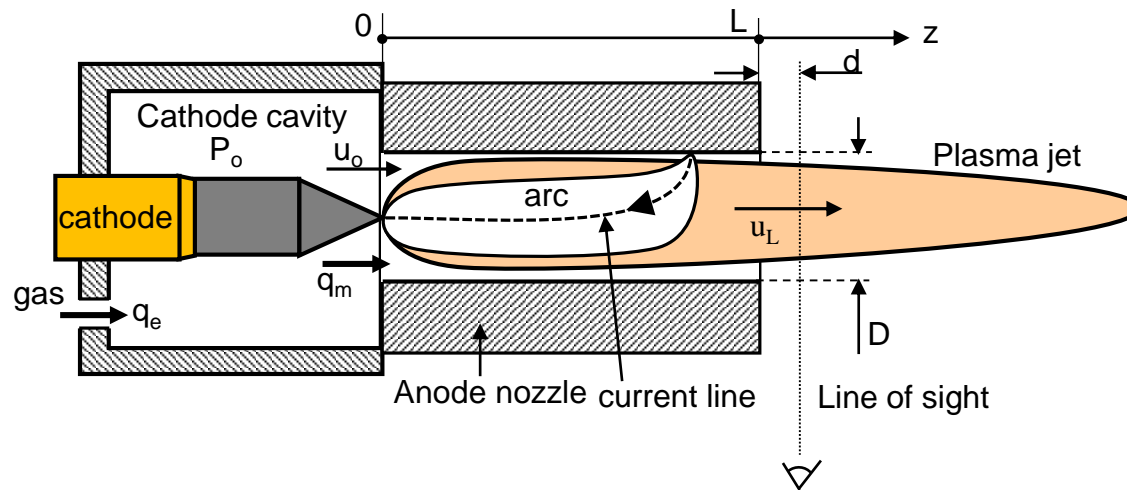
Measurements over one period



Reproducibility of triggering
example : $P_{elec}(trigger) = 1 \text{ kW}$



Parameter coupling in a dc plasma torch



- *Input parameters*: torch geometry, plasma forming gases, arc current
Arc voltage
- *Output parameters*: plasma specific enthalpy and speed
mass flow rate, gas pressure inside the cathode cavity
- Properties averaged over the channel cross at nozzle exit
- 0D, transient, linear, analytical model

Integrating 1-D time dependent conservation equations over the axial distance z
 L : nozzle length

Energy equation $m_p \frac{dh_L}{dt} + q_m (h_L - h_0) = -\alpha_{cr} L h_L$ $q_m h_0 = (V_{arc} - V_{elec}) I$

Momentum equation $L \frac{dq_m}{dt} + (u_L - u_0) q_m = -S(P_L - P_0) - \frac{L q_m}{\tau_f}$

Mass balance in the cathode cavity $q_e - q_m = V_{cav} \left(\frac{\partial \rho}{\partial P} \right)_{cav} \frac{dP_0}{dt}$

Fundamental frequency $\omega_0^2 = \left(\frac{\partial \rho}{\partial P} \right) \frac{S}{L V_{cav}}$

Linearizing conservation equations $\mathbf{x} = \bar{\mathbf{x}} + \mathbf{x}'$ $\mathbf{x} = \{ P_i \quad | \quad q_m \quad u_L \quad P_0 \quad \rho_L \quad h_L \}$

Non-dimensional fluctuating components $h = -\rho$ $u = q - \rho = q + h$

Conservation equations

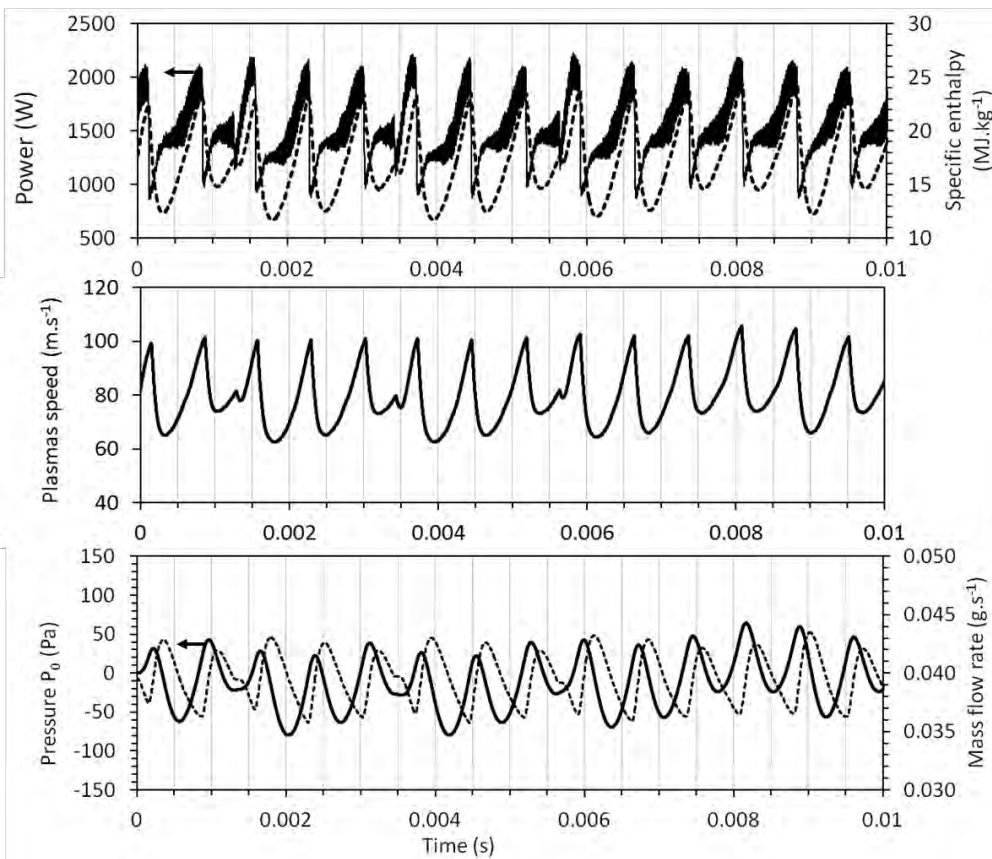
$$\dot{h} + \frac{h}{\tau} = \frac{p_i}{\tau} - \delta \frac{i}{\tau} - \frac{q}{\tau_{\text{res}}} \quad \ddot{q} + \frac{\dot{q}}{\tau_{\text{cav}}} + \omega_0^2 q = -\frac{\dot{h}}{\tau_{\text{res}}}$$

Characteristic times:

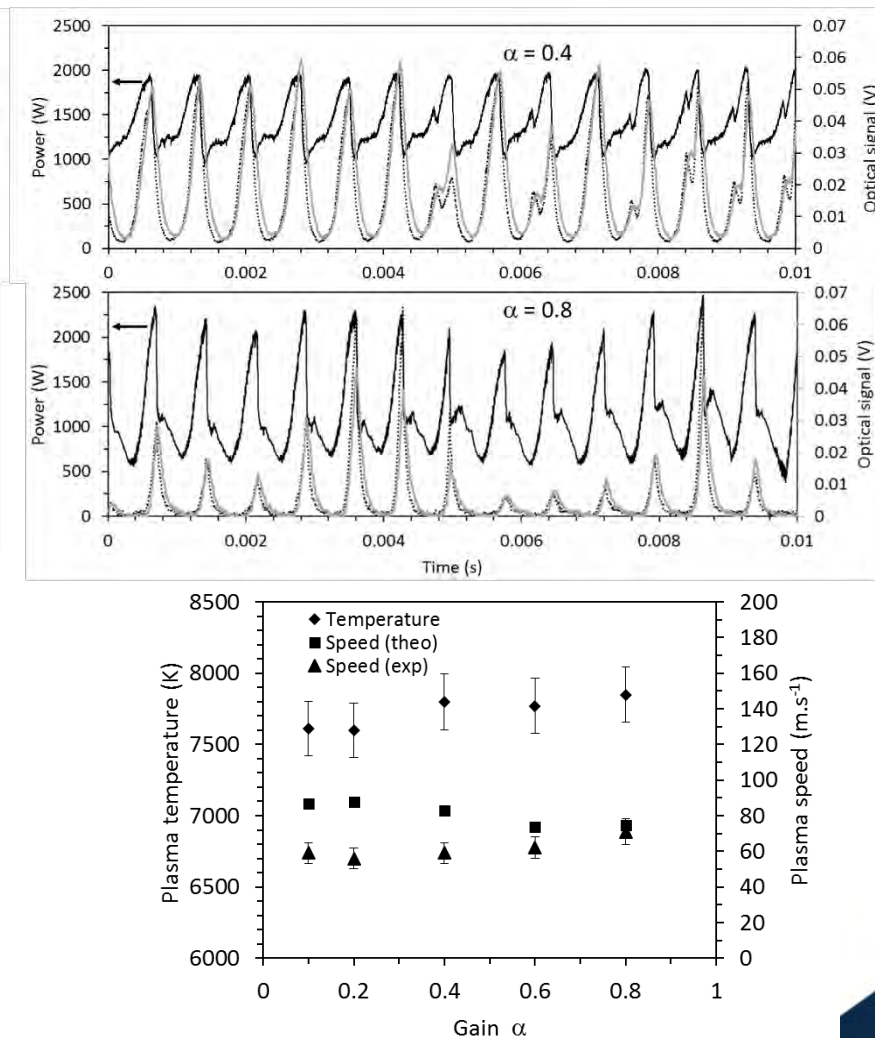
$$\frac{1}{\tau} = \frac{1}{\tau_{\text{res}}} + \frac{1}{\tau_{\text{tr}}} \quad \frac{1}{\tau_{\text{cav}}} = \frac{2}{\tau_{\text{res}}} + \frac{1}{\tau_{\text{f}}}$$

Residence time \nearrow Heat transfer time \nwarrow Viscosity effect \nwarrow

Calculated enthalpy and plasma speed

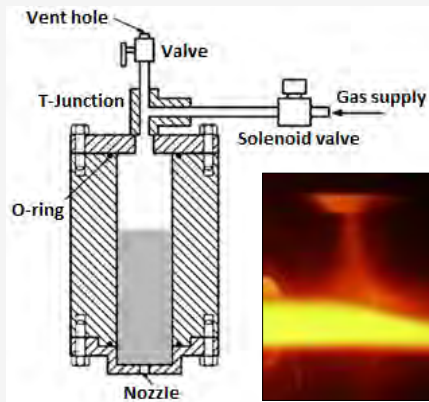


Plasma speed measurement

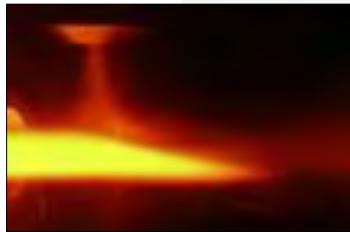


Liquid injection technology

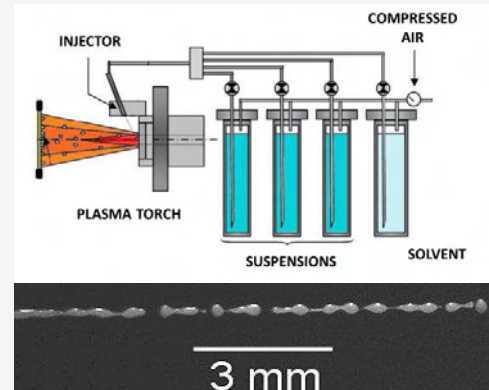
Atomization



\varnothing [2-100 μm]
 v : [5-60 $\text{m}\cdot\text{s}^{-1}$]



Mechanical injection



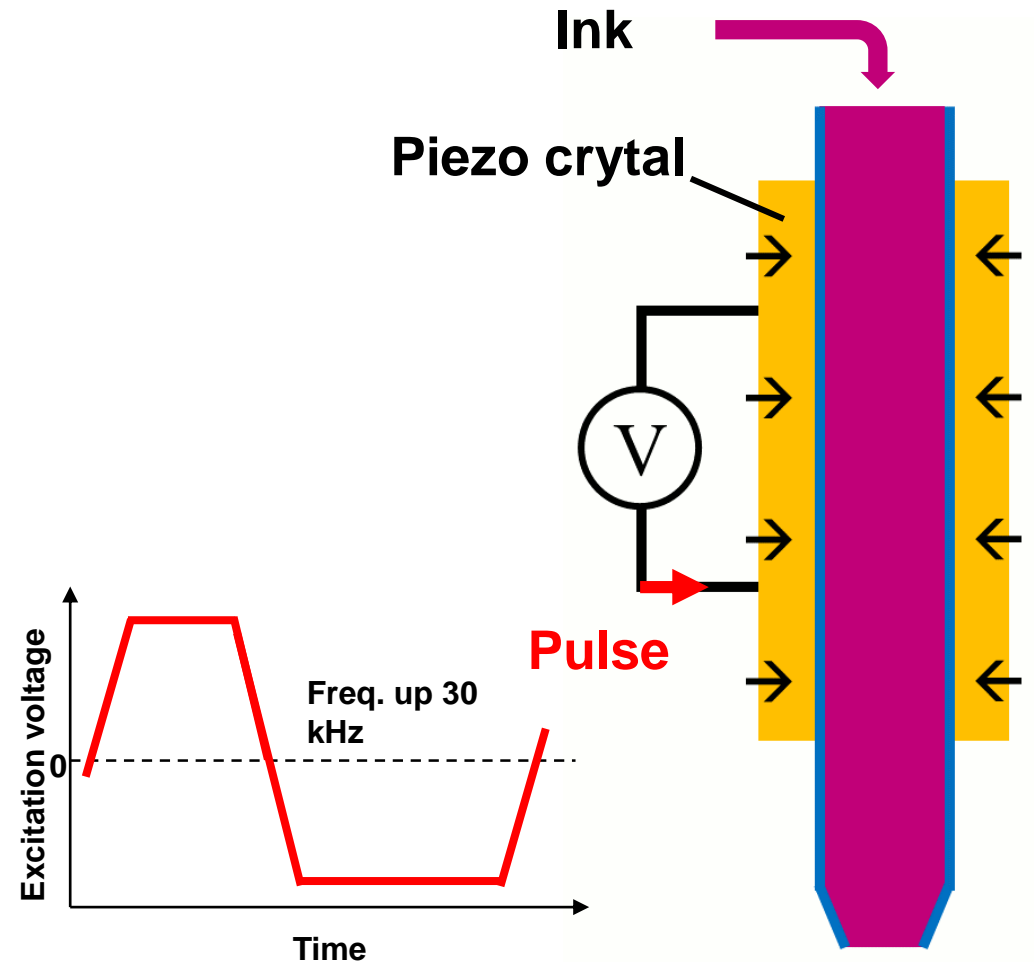
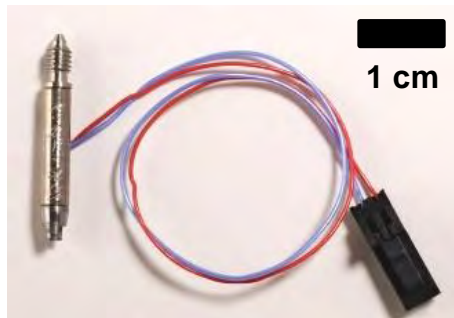
\varnothing 300 μm
 v : 20 $\text{m}\cdot\text{s}^{-1}$
 f : ~30 kHz

Ink-jet microdispenser

Ink-jet on demand

Specifications

- ✓ Individual droplet emission
- ✓ Injection frequency 1400 Hz
- ✓ Repeatable droplet emission

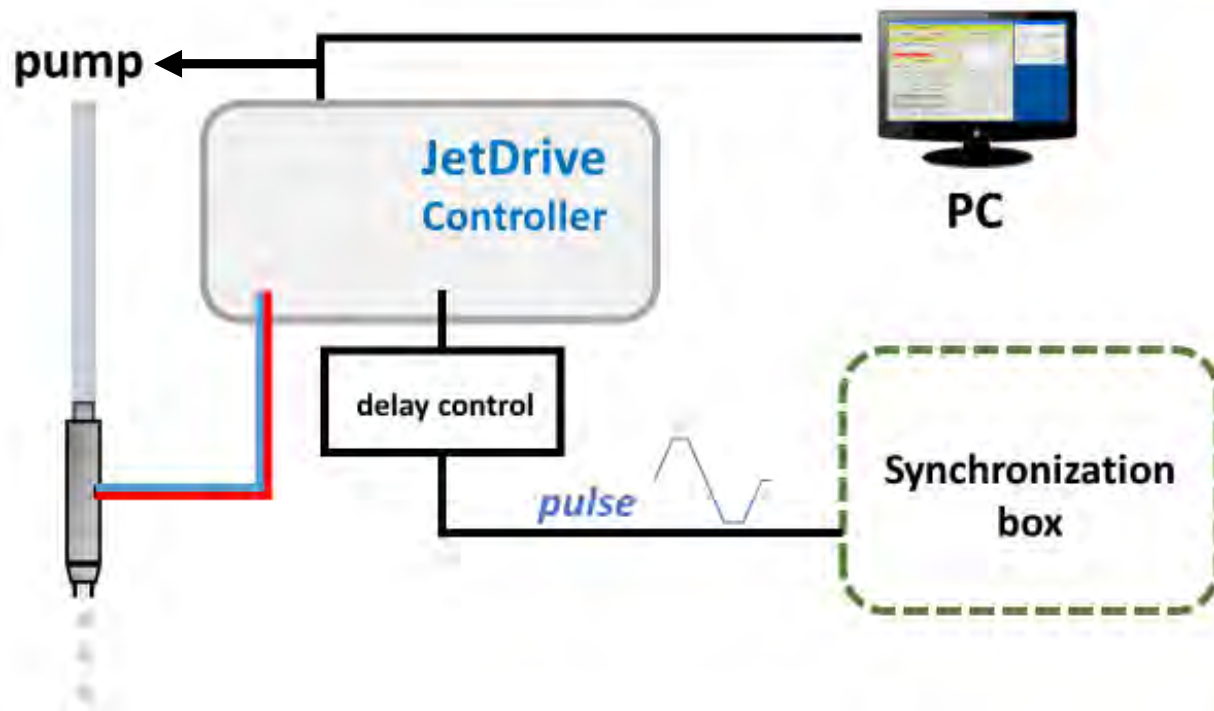


1 pulse = 1 droplet

$\varnothing 80 \mu\text{m}$, $3,2 \text{ m}\cdot\text{s}^{-1}$

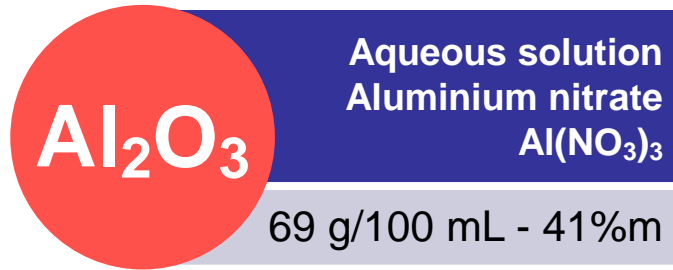


Ink-jet microdispenser

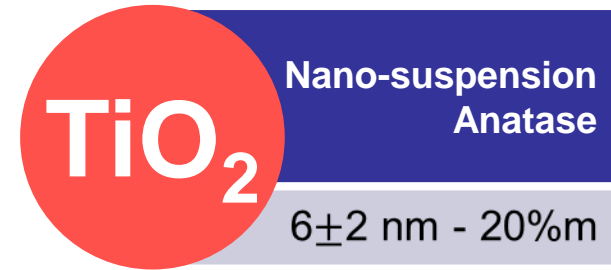


Materials

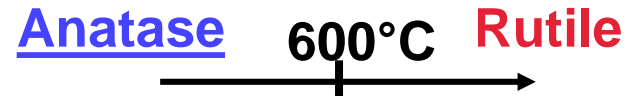
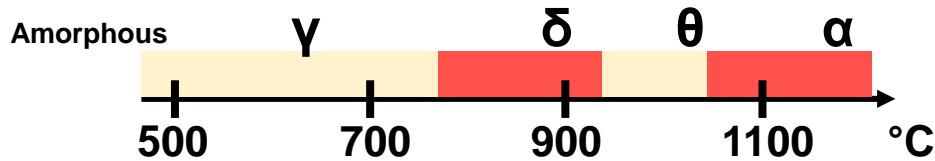
Aqueous inks



Al₂O₃
Aqueous solution
Aluminium nitrate
Al(NO₃)₃
69 g/100 mL - 41%*m*

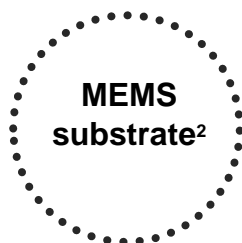


TiO₂
Nano-suspension
Anatase
6±2 nm - 20%*m*



Mechanical, chemical thermal,
electrical resistance

Photocatalytic
coatings and
Super-hydrophobicity



1 : L. Pawlowski, Surf. Coat. Technol. (35),1988.
2 : C. J. Li et al., Wear, (260), 2006.
3 : C. C. Stahr et al., J. Therm. Spray Technol. (16), 2007.

4 : K. Nakata et A Fujishima, J. Photochem. Photobiol. C Photochem. Rev., (13), 2012.
5 : N. Sharifi et al., Surf. Coat. Technol. (289), 2016.

Inks formulation

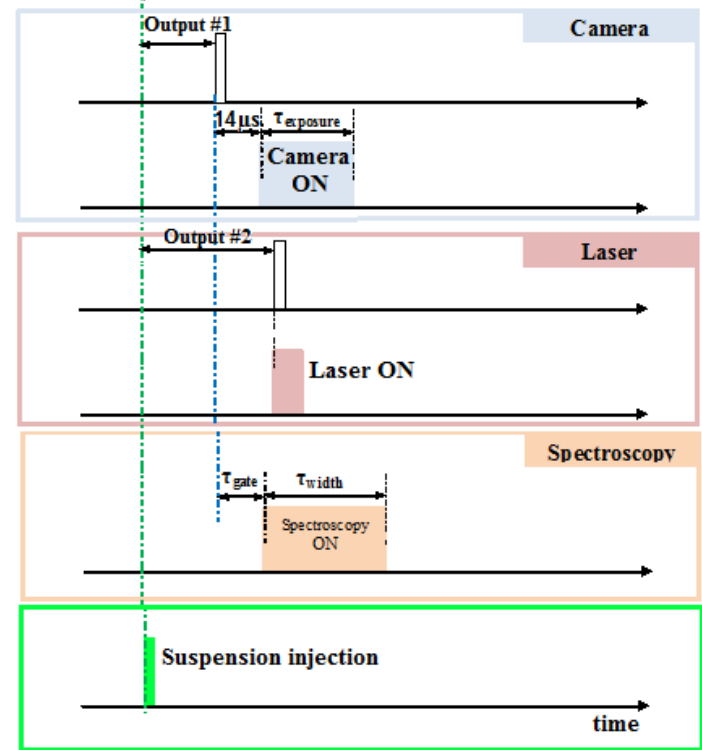
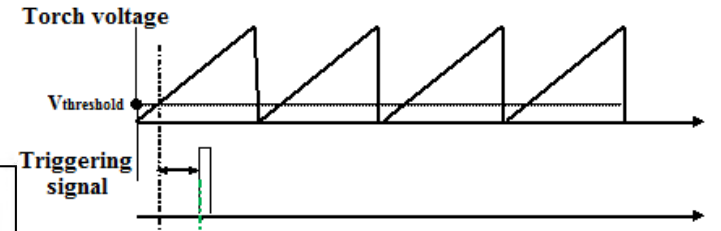
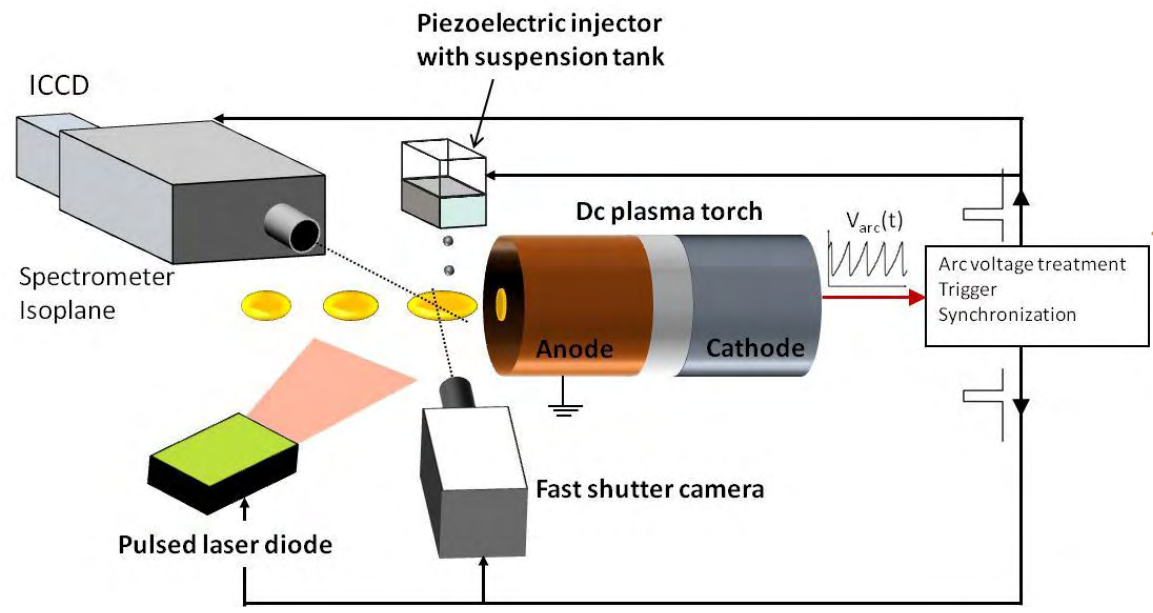
				Nano-suspension TiO ₂ Anatase	Aqueous solution Aluminium nitrate Al(NO ₃) ₃
pH	➔	[2-11]	Ammoniac	2	1 ➔ 2
Viscosity η (mPa.s)	➔	4-8	Glycerol	1 ➔ 5	1 ➔ 7
Surface tension γ (mN.m ⁻¹)	➡	20-70	Surfactant	74 ➔ 39	74 ➔ 41
Ejection ratio Z*		[1-10]**	$Z = \frac{Re}{\sqrt{We}} = \frac{\sqrt{\rho \gamma r}}{\eta}$	59 ➔ 8	57 ➔ 6

Inks formulation

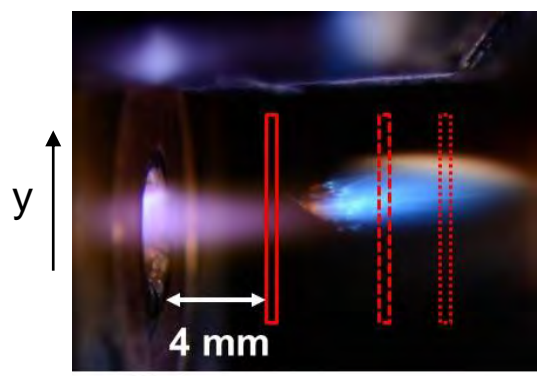
				Nano-suspension TiO ₂ Anatase	Aqueous solution Aluminium Nitrate Al(NO ₃) ₃
				Suspension 58% Glycerol 41% BRIJ58 <1%	Nitrate Al 27% Water 41% Glycerol 30% Ammoniac 2% BRIJ58 <1%
pH	➔	[2-11]	Ammoniac	2	1 ➔ 2
Viscosity η (mPa.s)	➔	4-8	Glycerol	1 ➔ 5	1 ➔ 7
Surface tension γ (mN.m ⁻¹)	➡	20-70	Surfactant	74 ➔ 39	74 ➔ 41
Ejection ratio Z^*		[1-10]**		59 ➔ 8	57 ➔ 6

$$Z = \frac{Re}{\sqrt{We}} = \frac{\sqrt{\rho \gamma r}}{\eta}$$

Experimental set-up

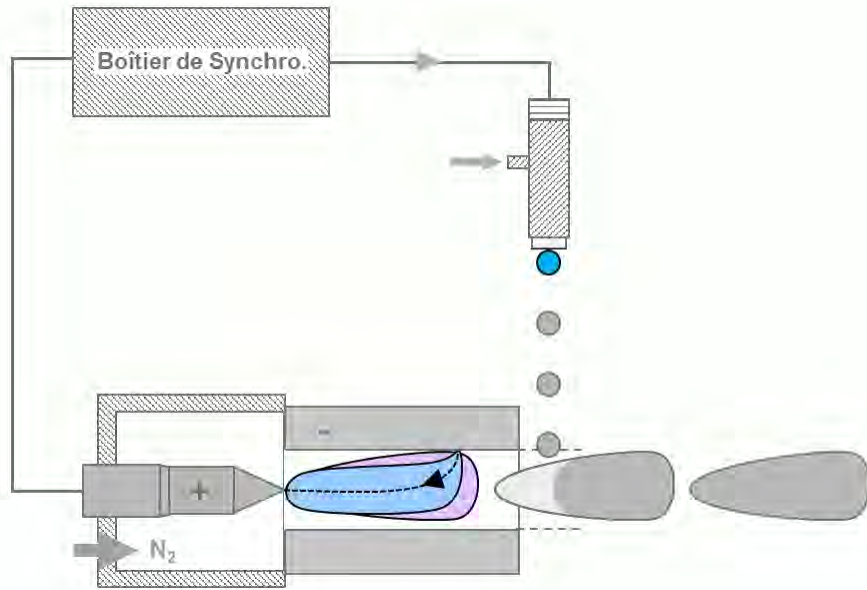


- ◆ Time-resolved optical emission spectroscopy observations

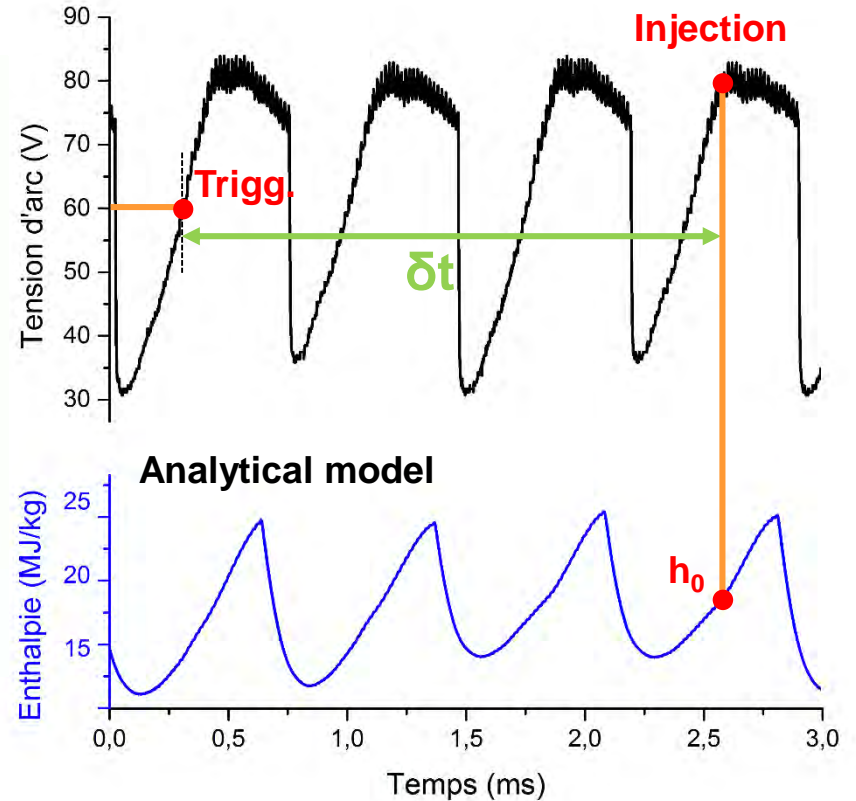


Droplets emission and injection

Plasma : 60 m.s^{-1} > droplets : $1-3 \text{ m.s}^{-1}$



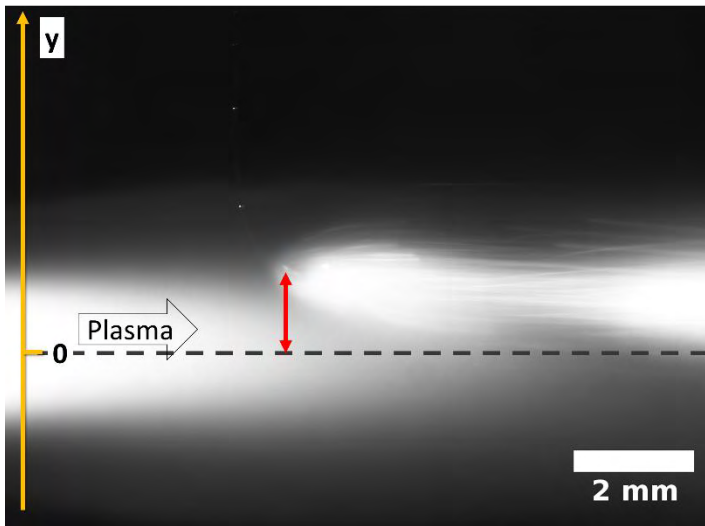
Distribution of interception heights by plasma
Anatase suspension



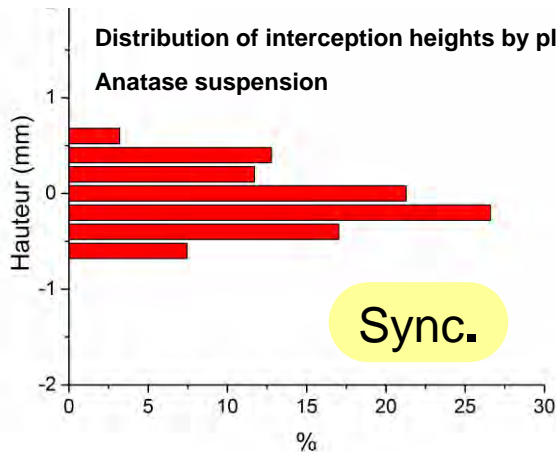
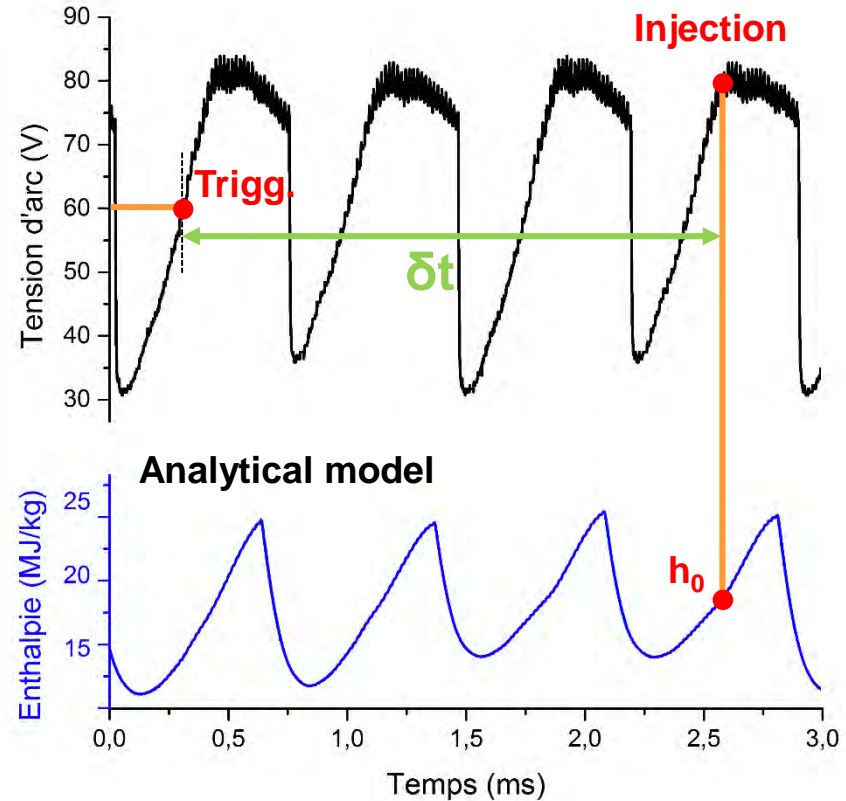
Voltage trigger 60 V

Droplets emission and injection

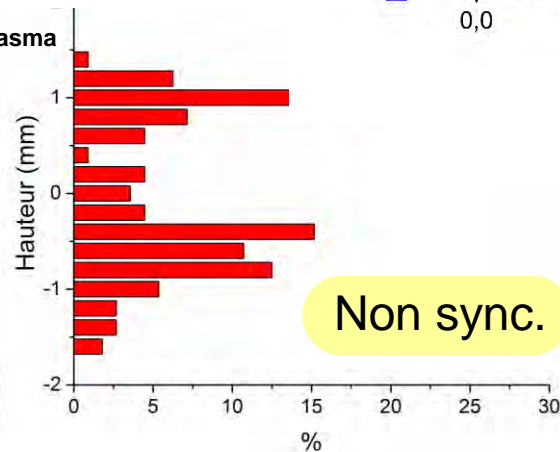
Plasma : 60 m.s⁻¹ > droplets : 1-3 m.s⁻¹



Exposure time : 50 μs



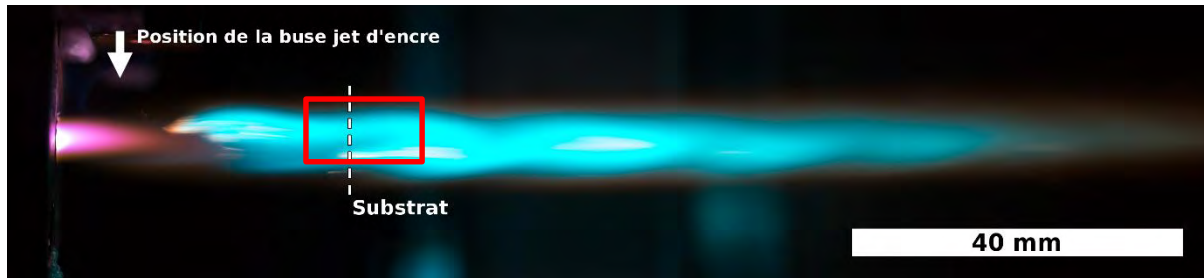
Sync.



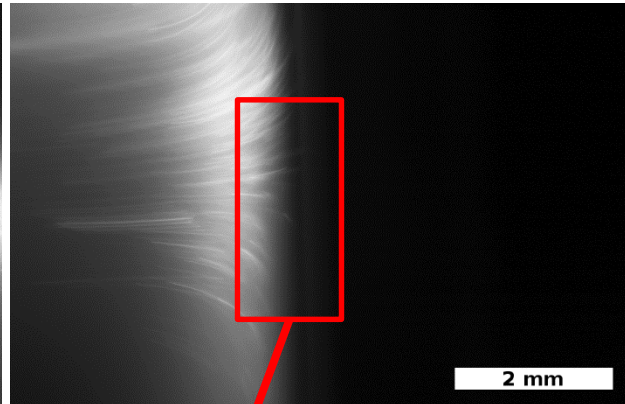
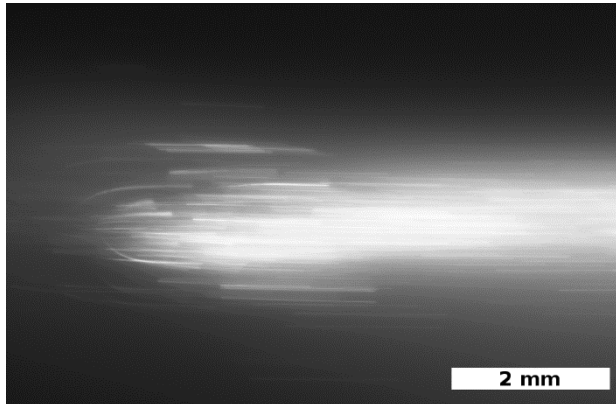
Non sync.

Voltage trigger 60 V

SPPS – Aluminium nitrate solution



Stokes number 0,7



Weber number < 1

No mechanical fragmentation

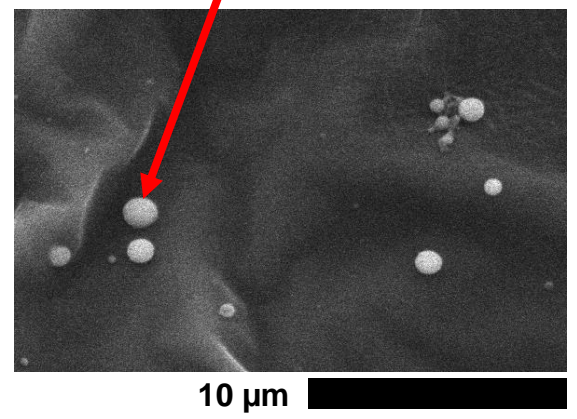
Acceleration time

$$\tau_{acc} = \frac{\rho_l \cdot d_g^2}{18\eta} \quad 2,3 \text{ ms}$$

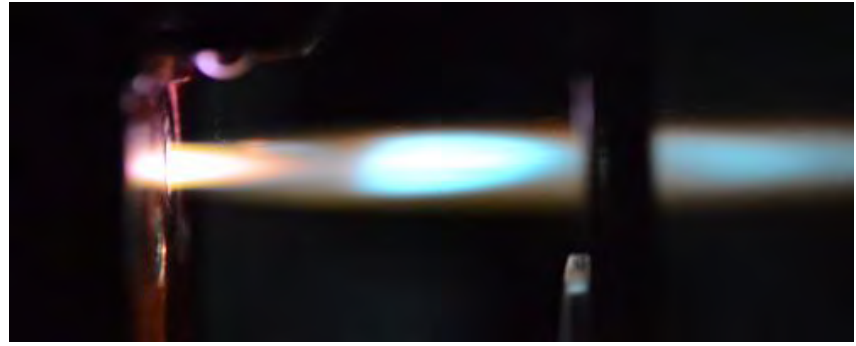
Vaporization time of solvent

110 μs

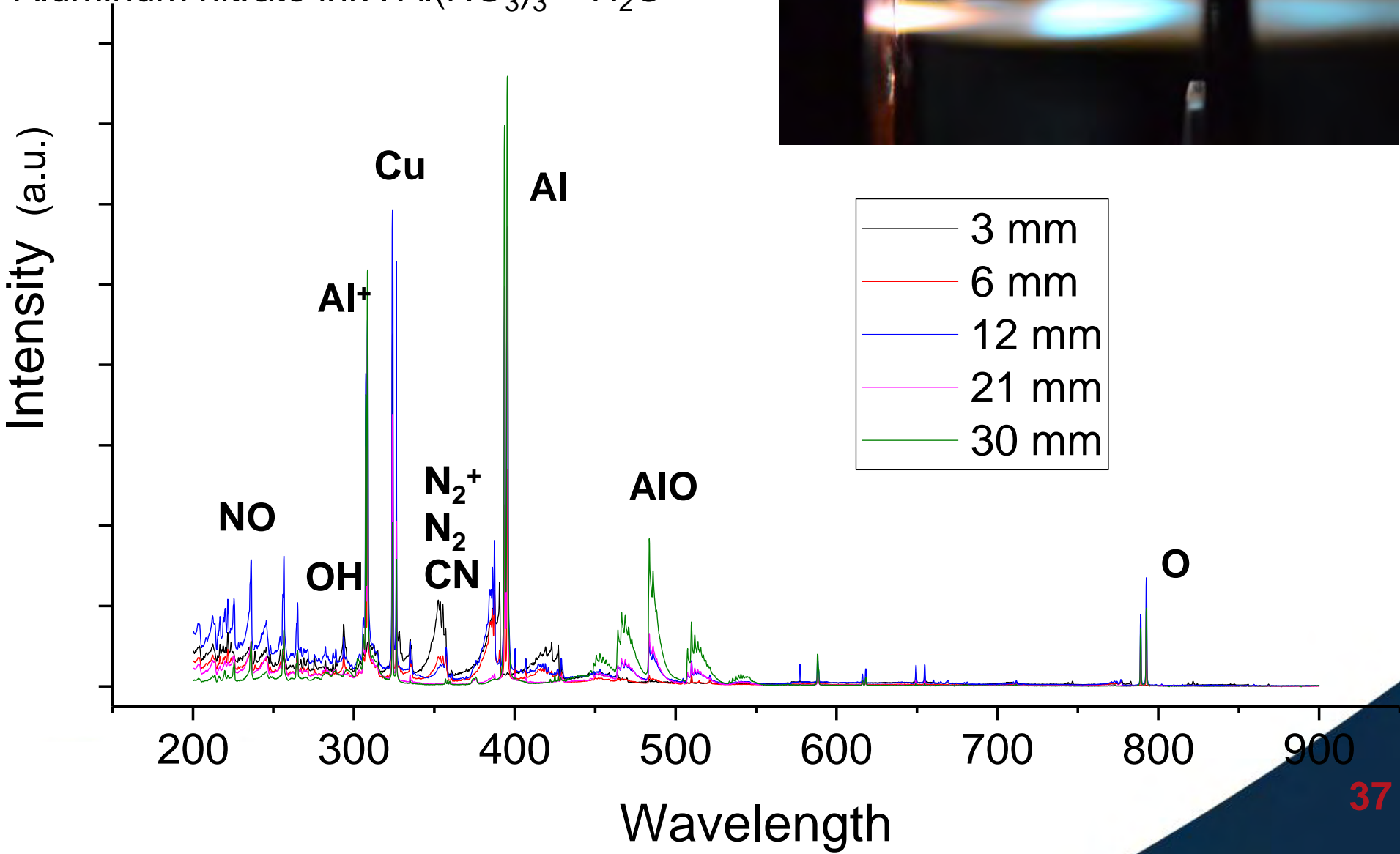
$$\tau_{vap} = \frac{\rho_l \cdot L_v}{4Nu \cdot a_\phi} \left(\frac{d_g^2}{h_p} \right) \left[1 - \left(\frac{d_s}{d_g} \right)^2 \right]$$

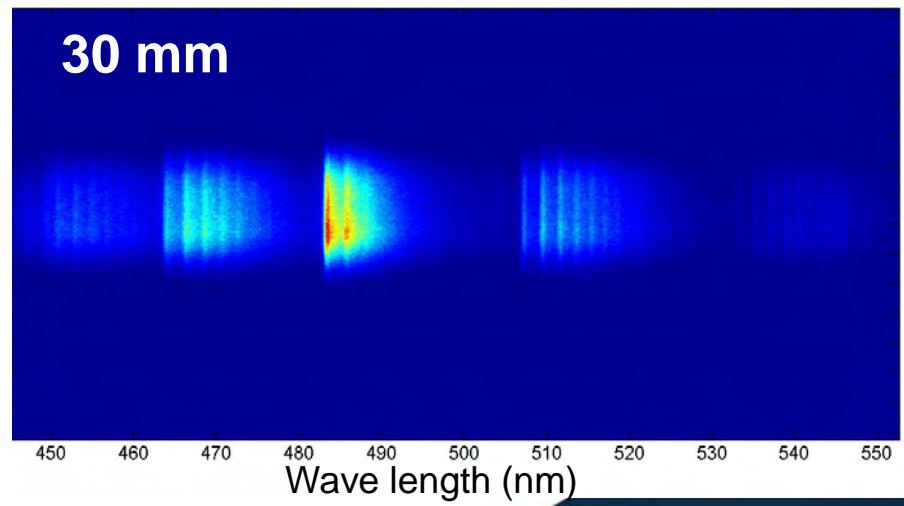
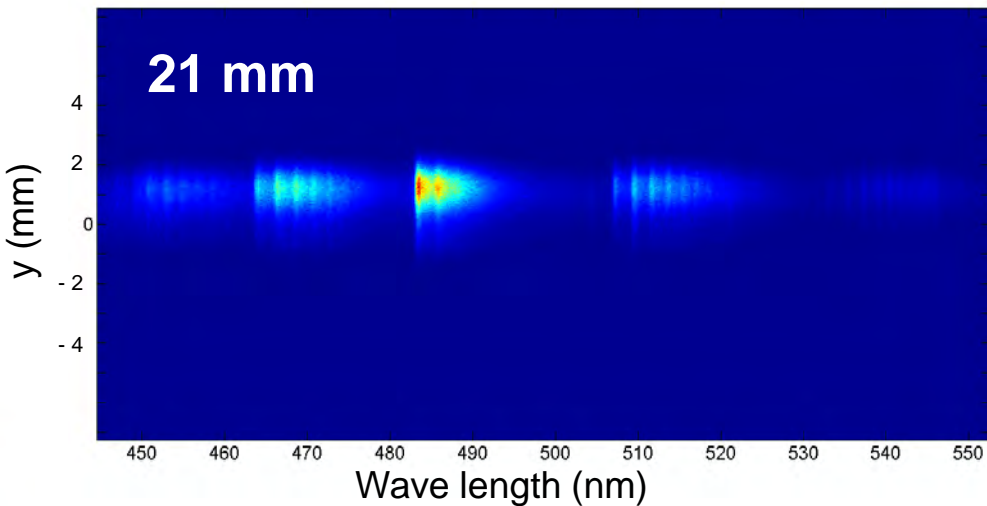
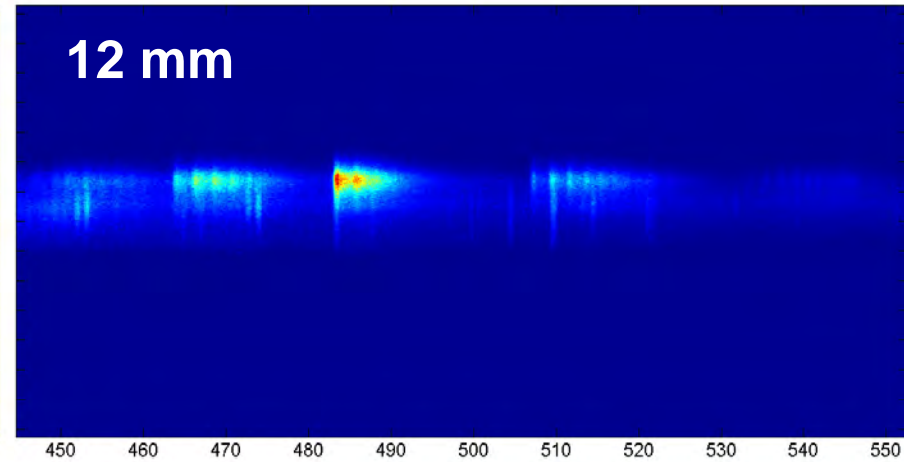
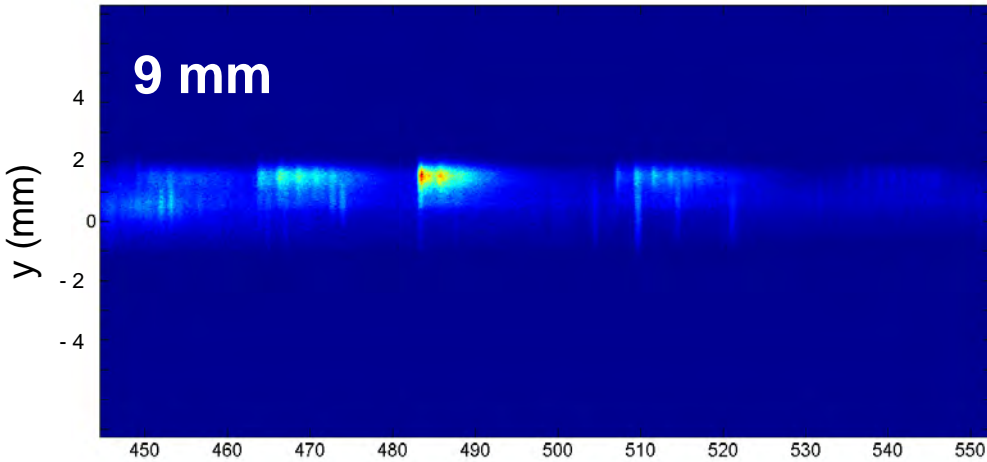
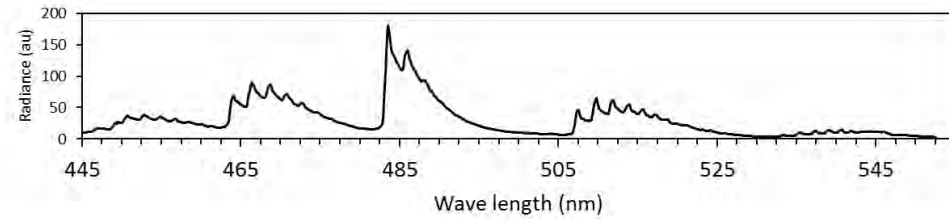


◆ **Solution Precursor Plasma Spraying**

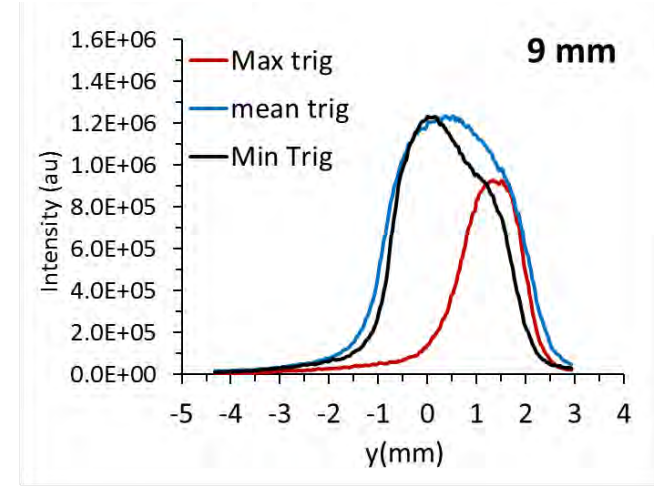
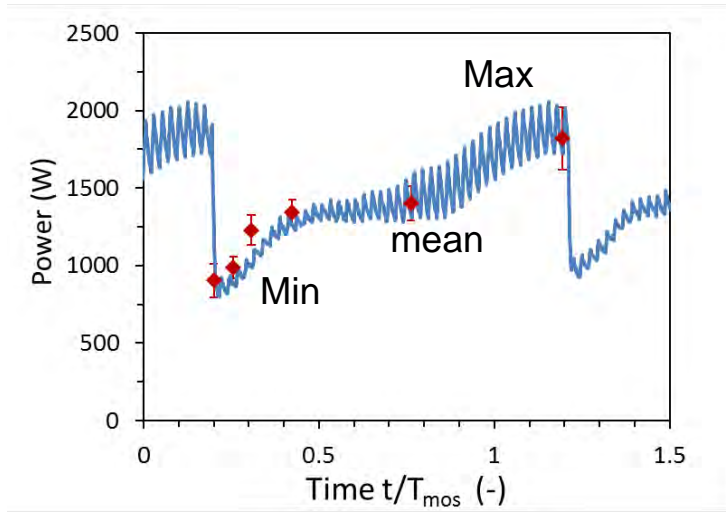


Aluminum nitrate ink : $\text{Al}(\text{NO}_3)_3 + \text{H}_2\text{O}$

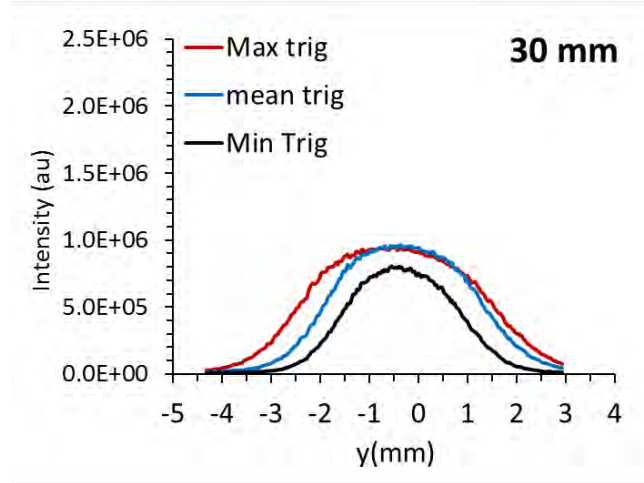


AIO ($B^2\Sigma^+ \rightarrow X^2\Sigma^+$)Time-averaged trajectories of
AIO emission

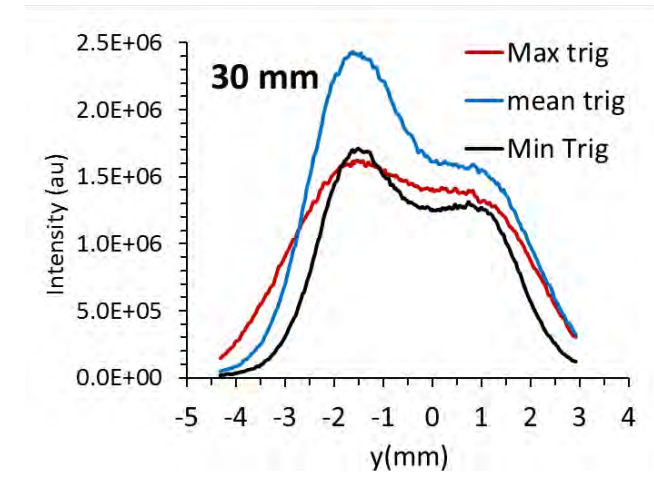
Time-resolved emission y-profiles of Al and AlO



Al (II)
308 nm

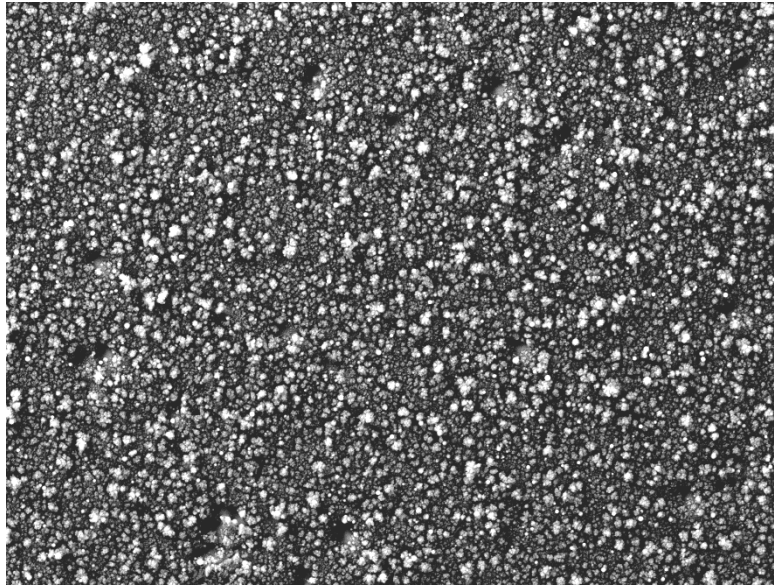


Al (II)
308 nm

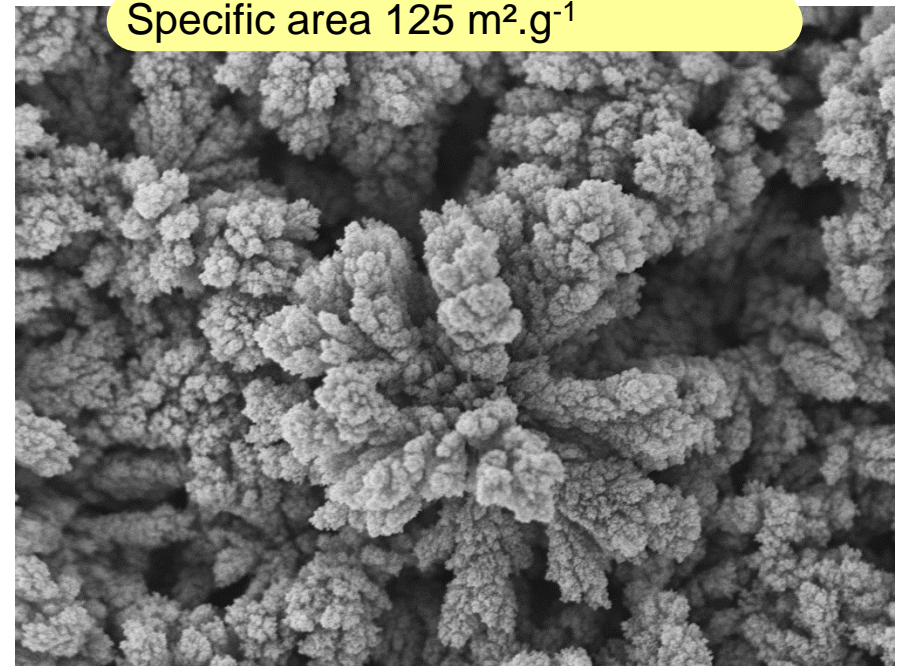


AlO
($B^2\Sigma^+ \rightarrow X^2\Sigma^+$)

SPPS – Aluminium nitrate solution

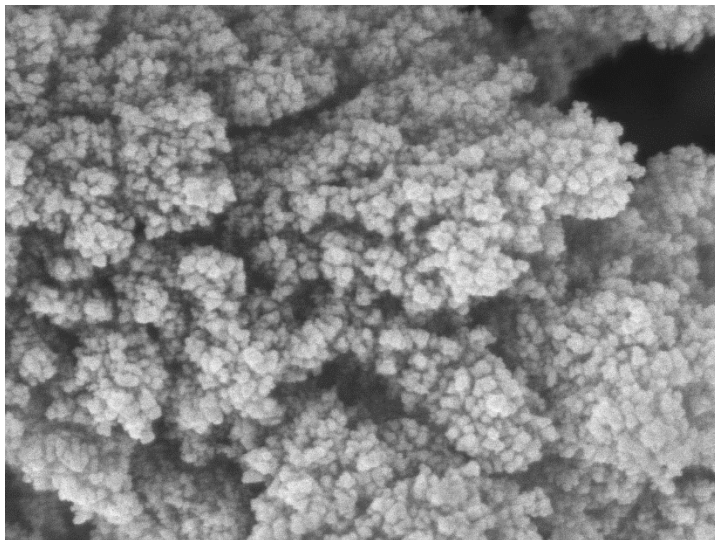


50 μm

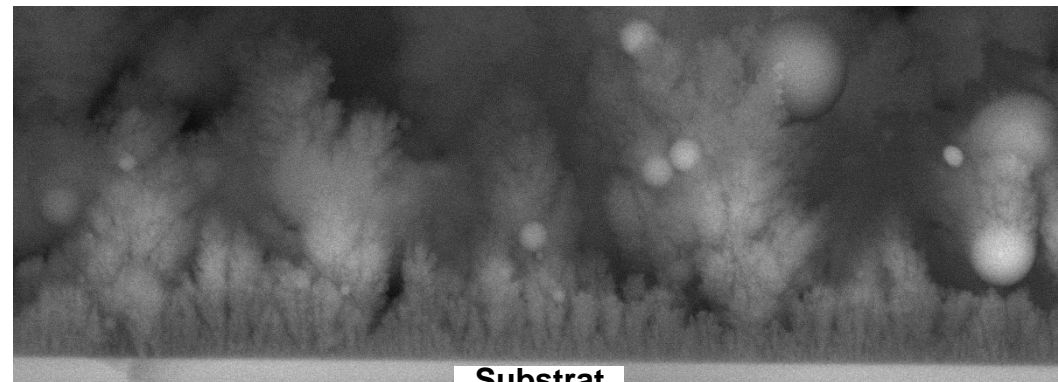


Specific area 125 m².g⁻¹

2 μm



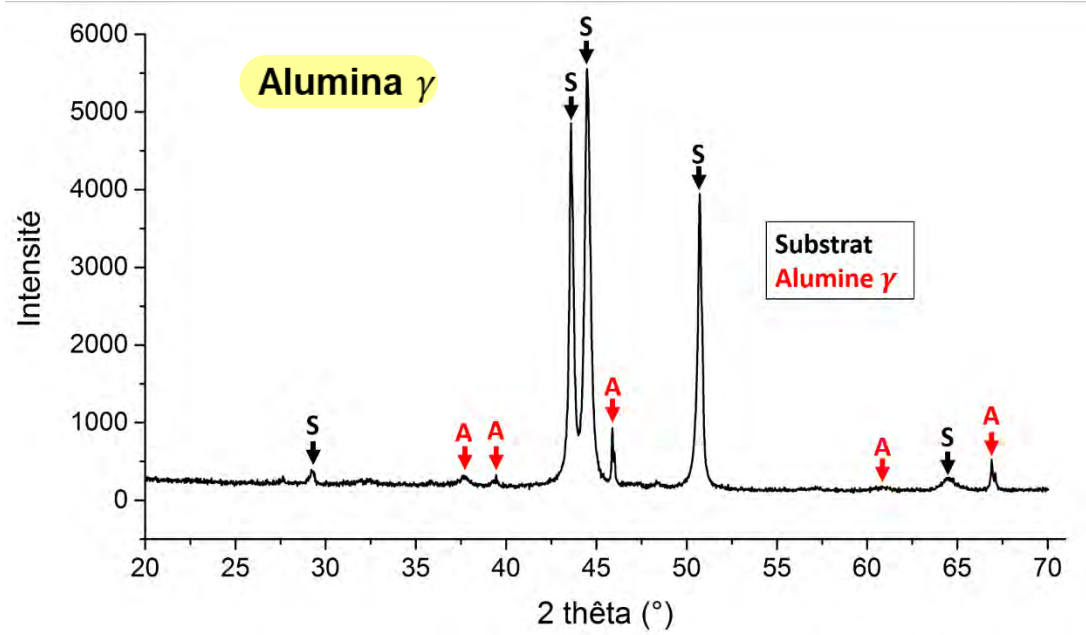
200 nm



Substrat

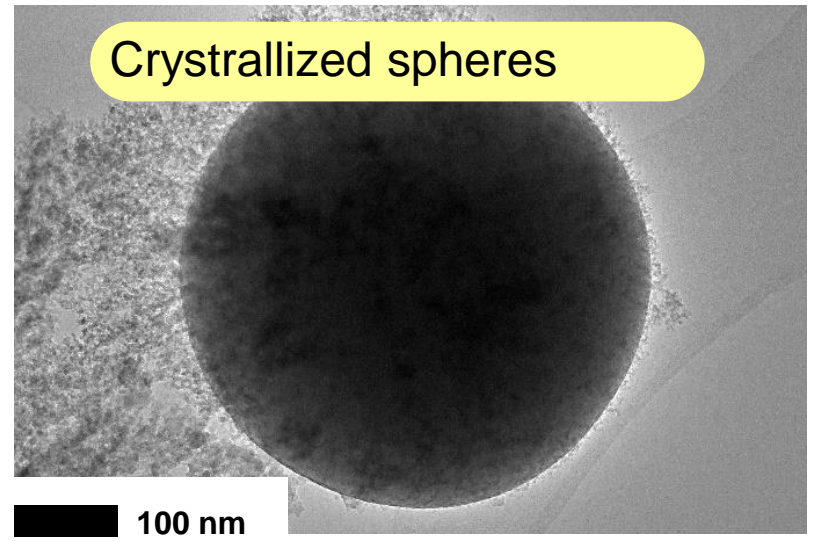
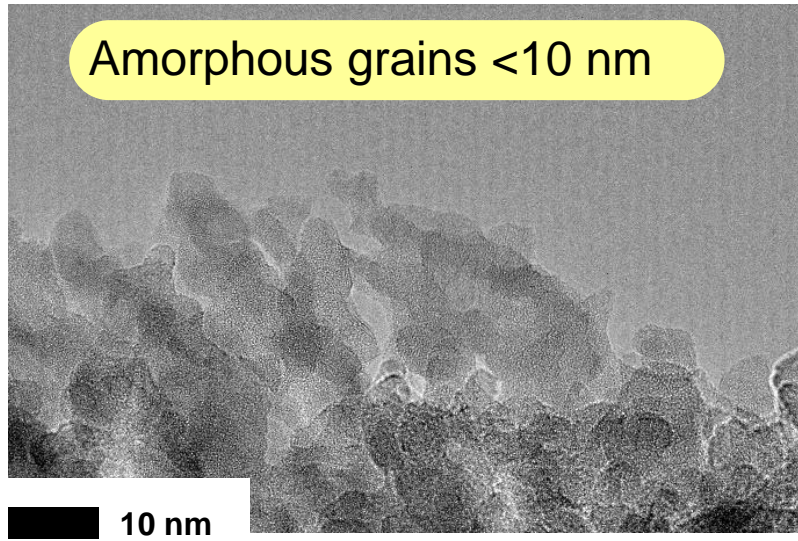
2 μm

SPPS – Aluminium nitrate solution



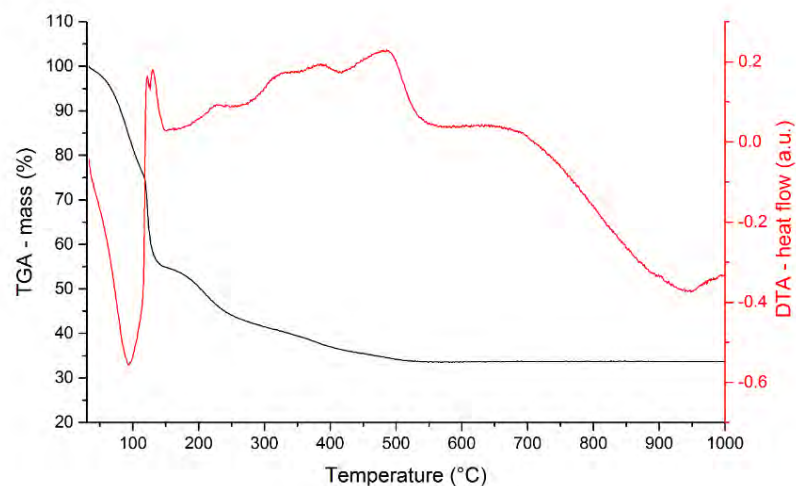
Al et O ratio $\frac{2}{3}$

Cohesive coatings but low adherence

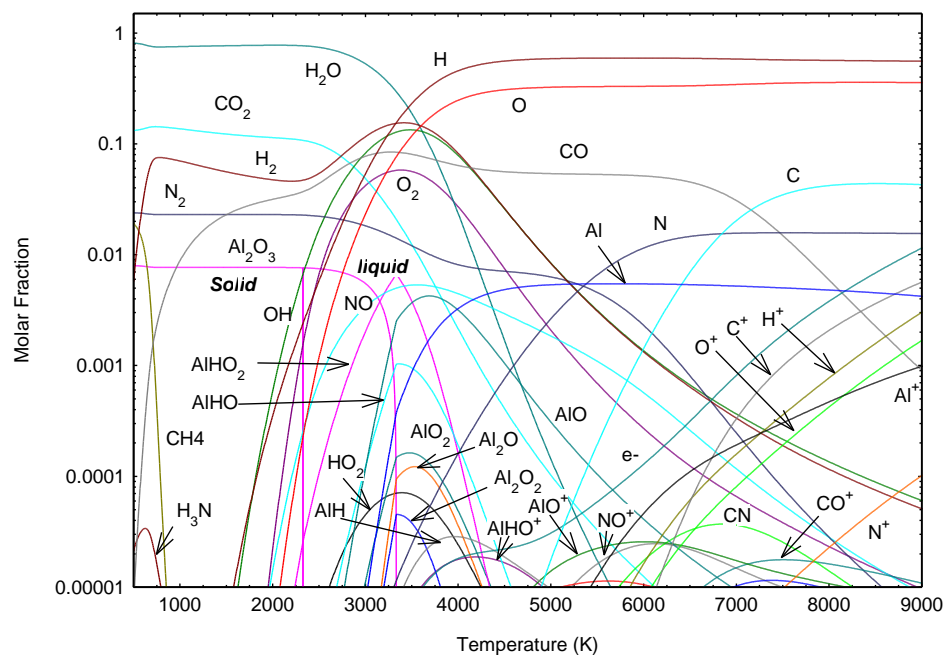


SPPS – Aluminium nitrate solution

TGA/DTA analysis

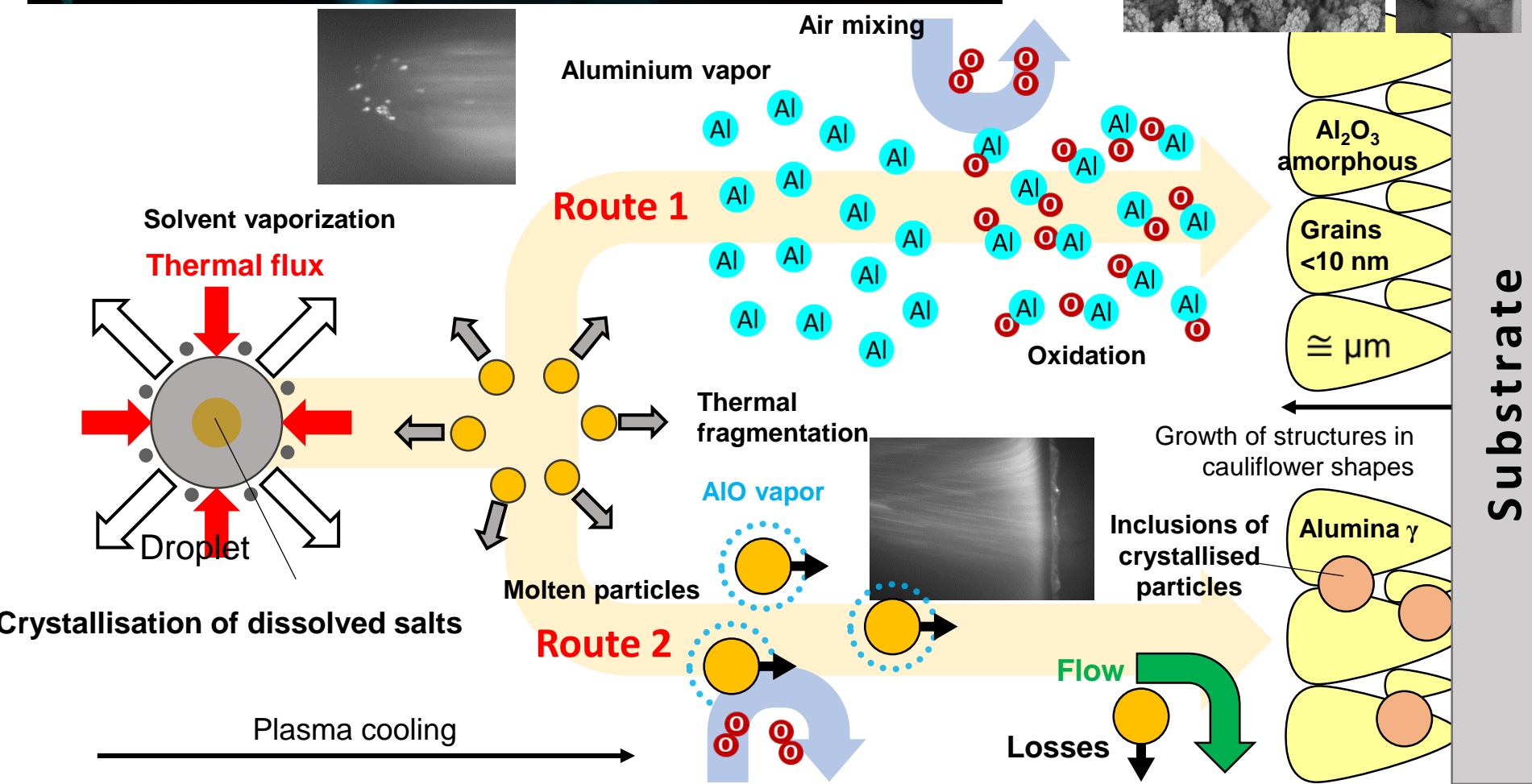
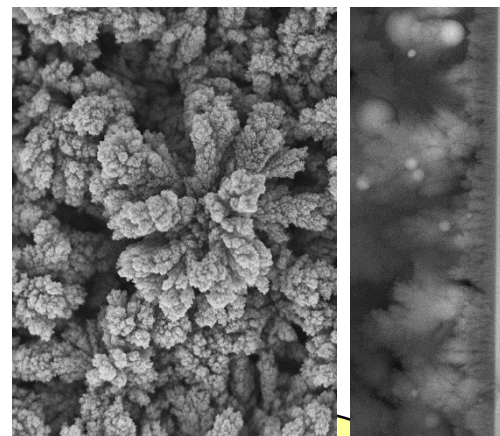
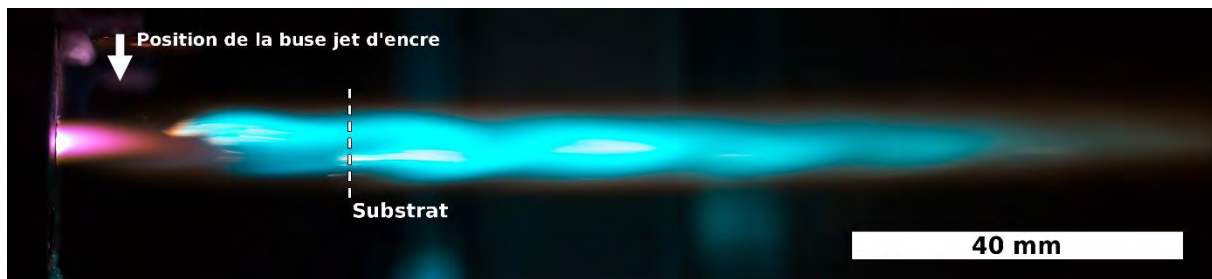


Thermodynamic calculations



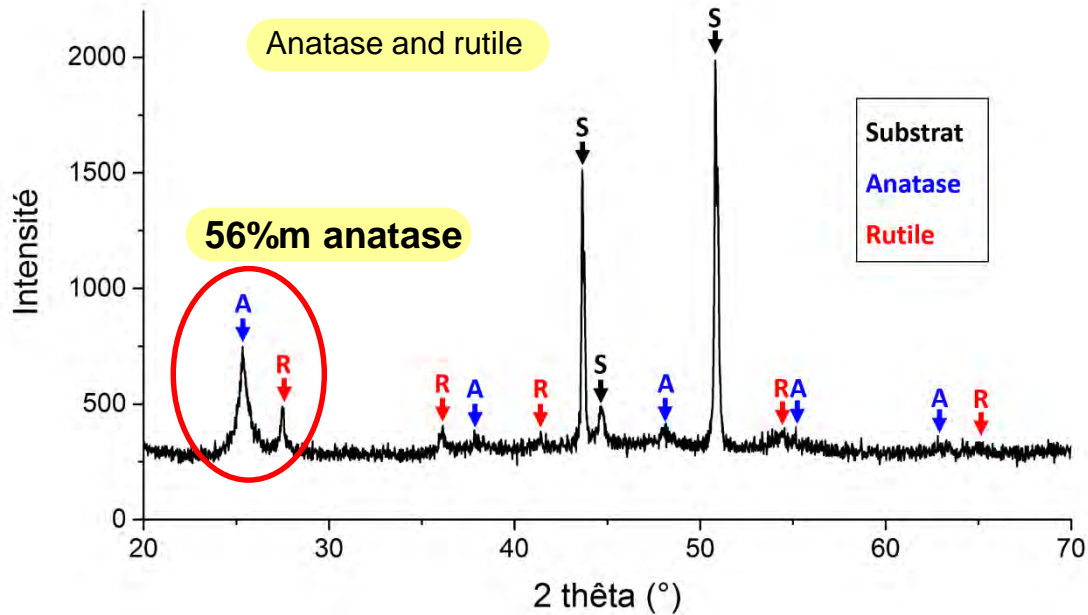
P. André

SPPS – Aluminium nitrate solution



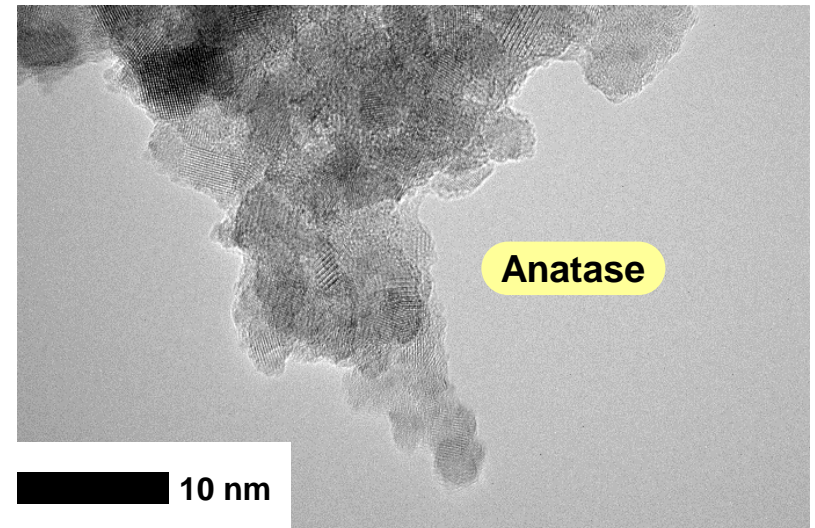
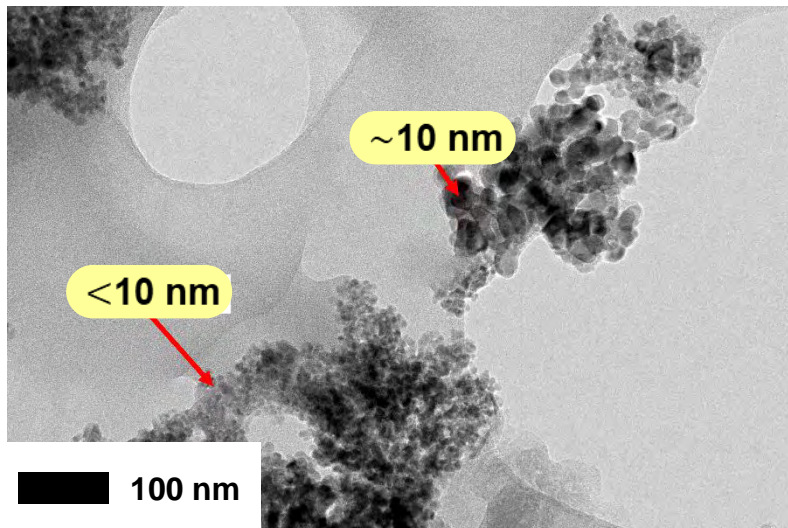
SPS – Anatase suspension

(Suspension of nanoparticles 6 nm)

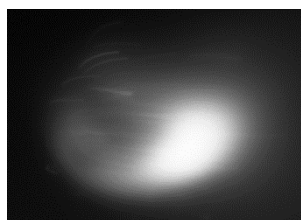
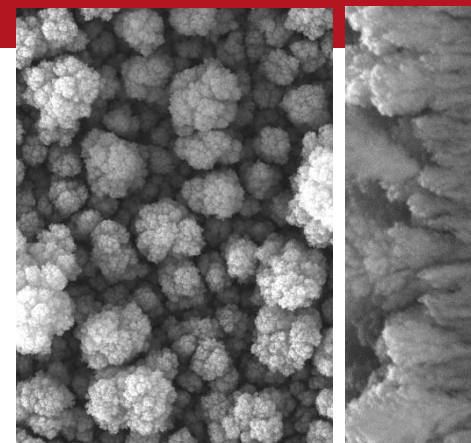


Ti et O ratio 1/2

Weak adherence of coatings on silicon wafer

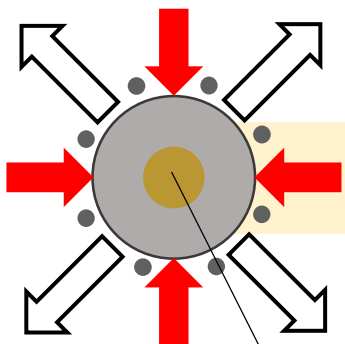


SPS – Anatase suspension



Solvent vaporization

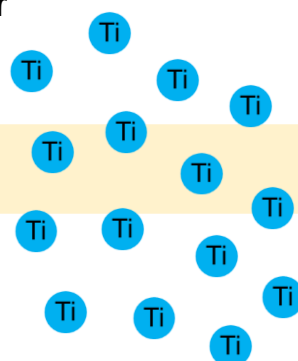
Thermal flux



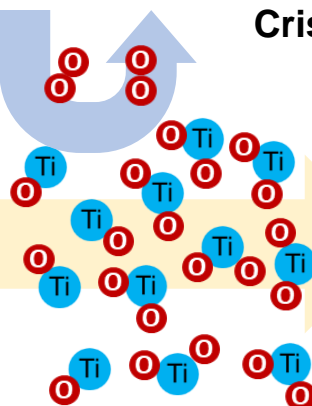
Suspension of anatase particles (6 nm)

Titanium vapor

Route 1



Oxidation



Cristallites 10 nm et <10 nm

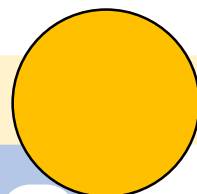
Anatase

≈ μm

Substrate

Thermal fragmentation

Route 2



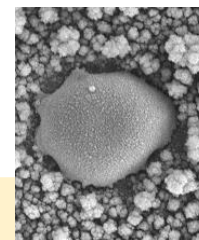
Growth of crystallized structures in cauliflower shapes

μm molten particles

Rutile ?

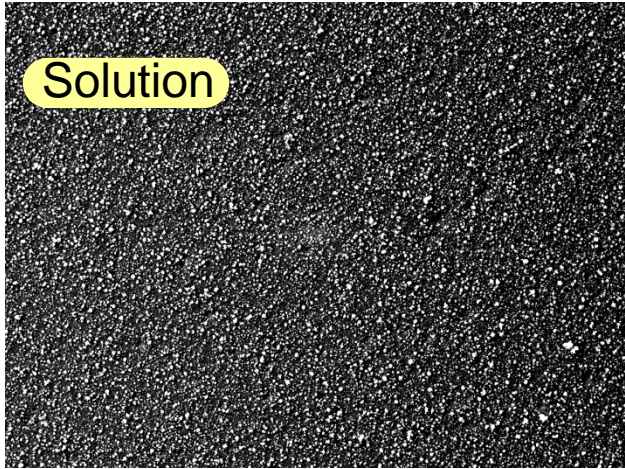
Plasma cooling

Air mixing

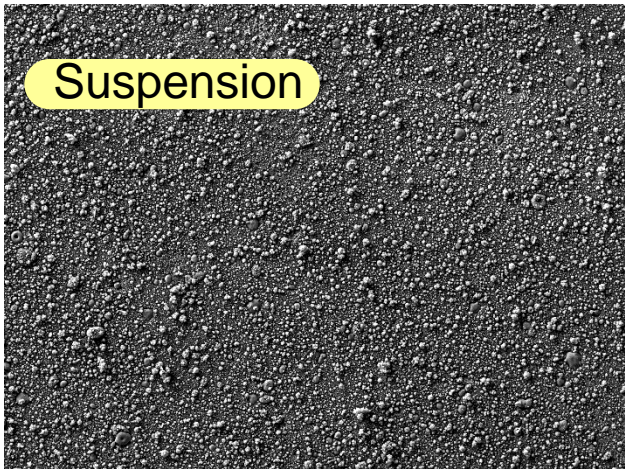


Influence of the synchronisation

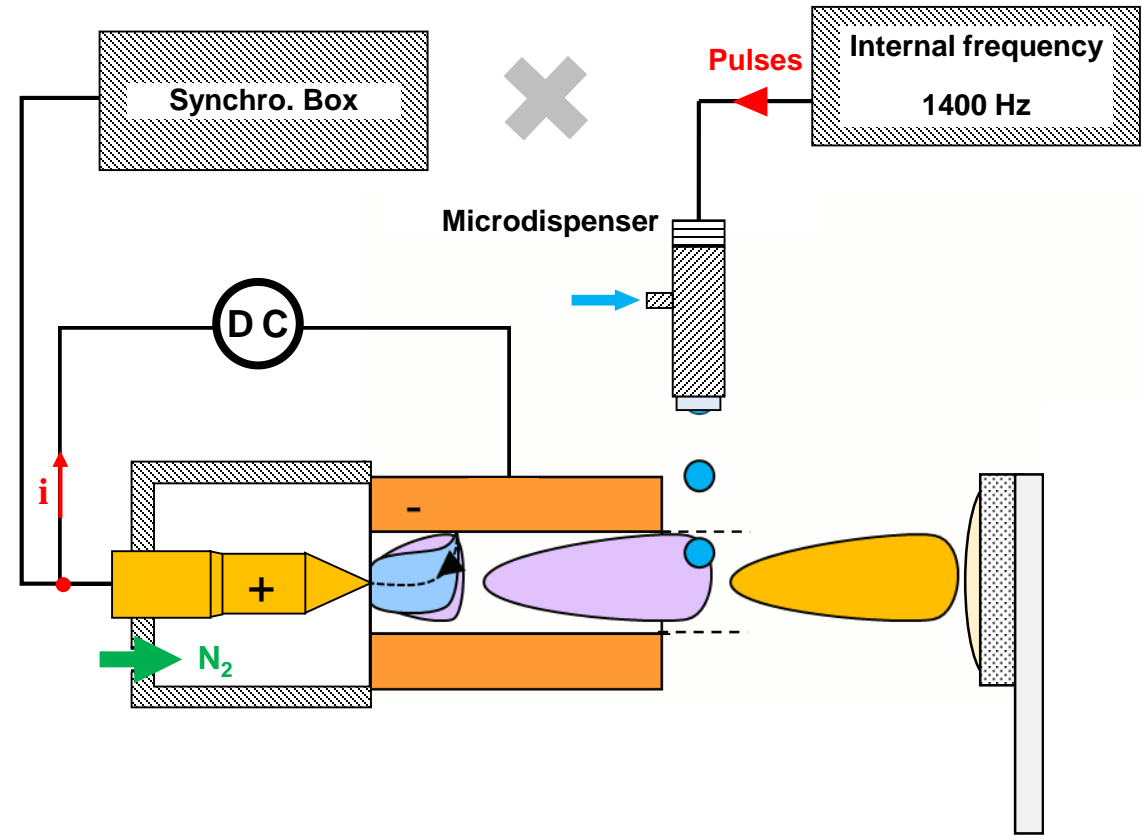
Sync



100 μm



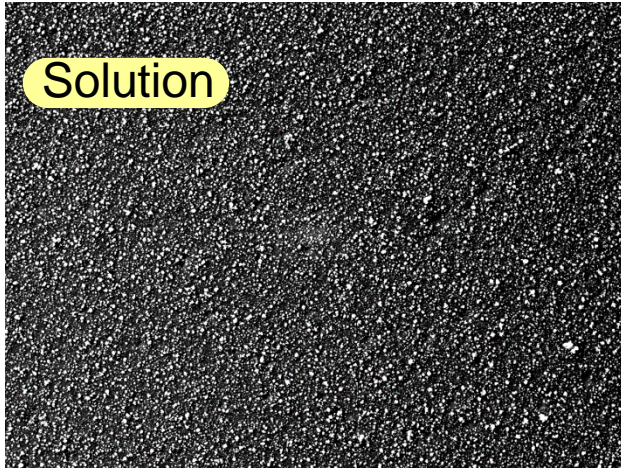
100 μm



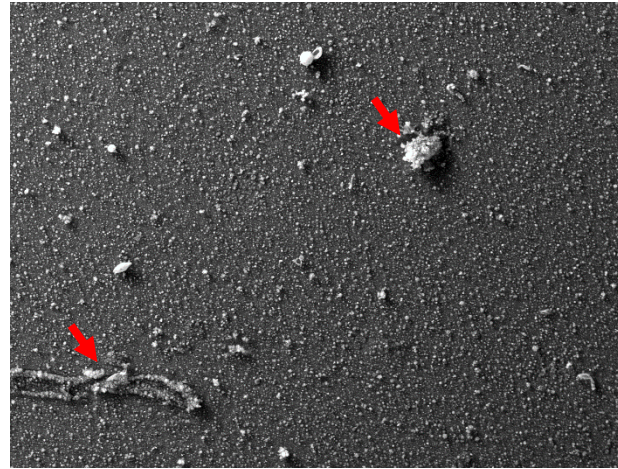
Influence of the synchronisation

Sync

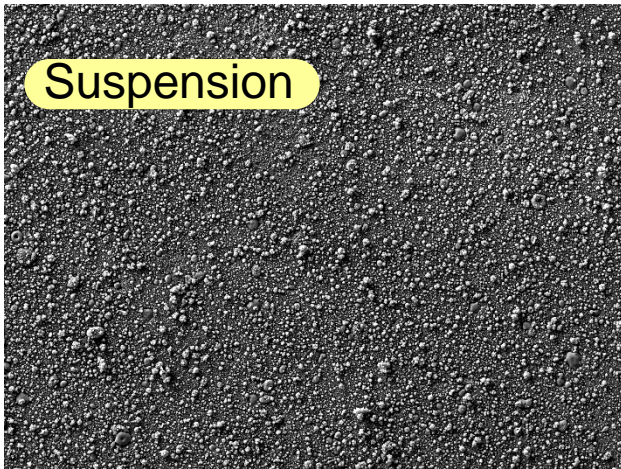
Non sync.



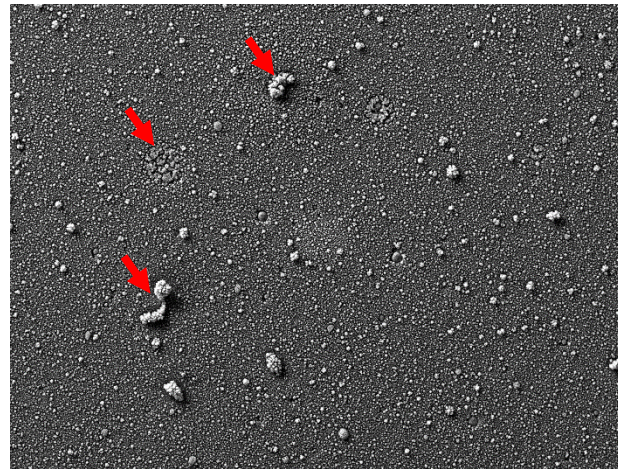
100 μm



100 μm



100 μm

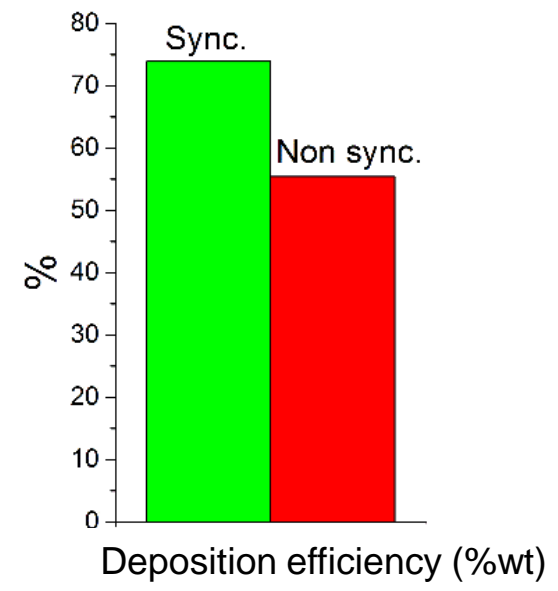
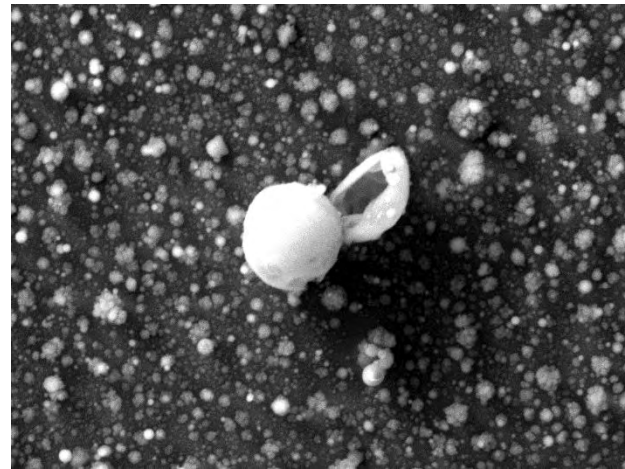
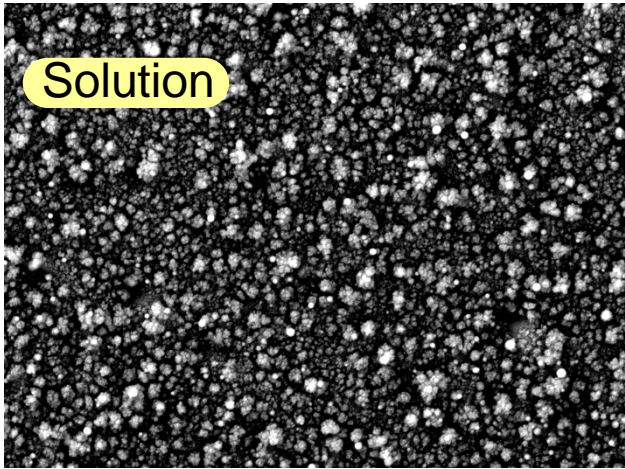


100 μm

Influence of the synchronisation

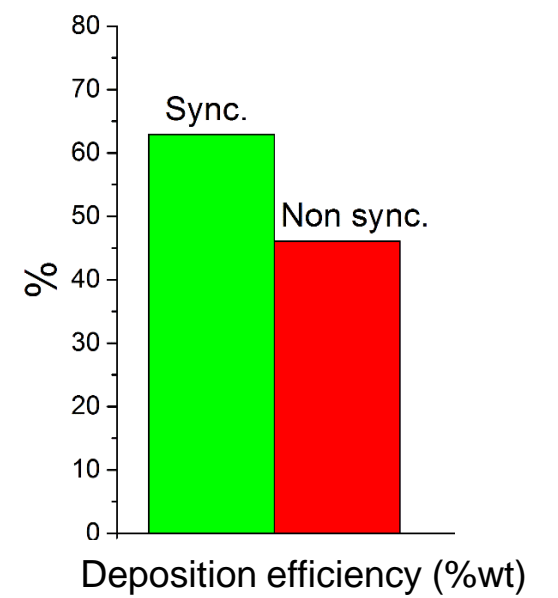
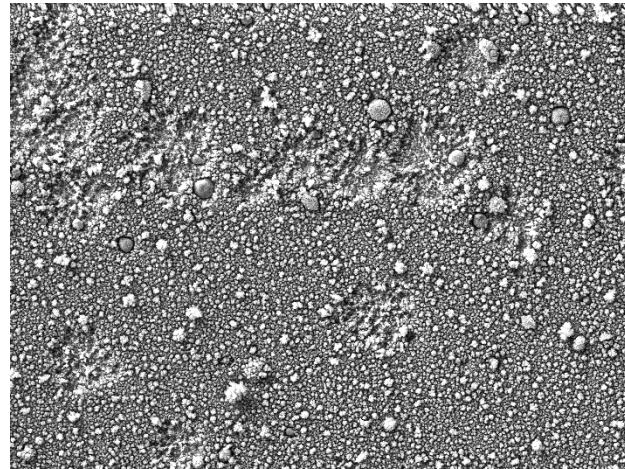
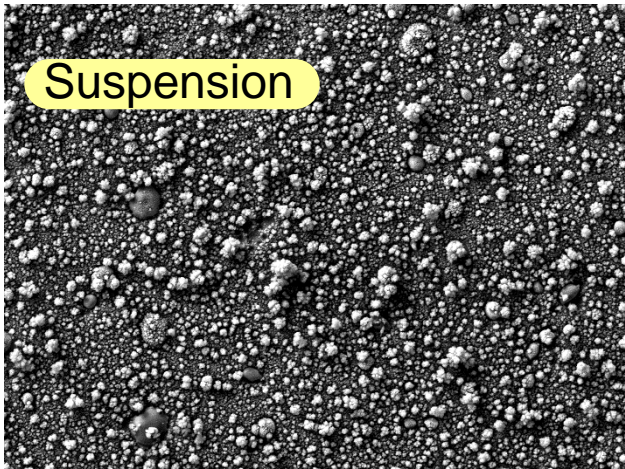
Sync.

Non sync.



20 μm

20 μm



50 μm

50 μm

Conclusions

Arc current modulation

Stabilization effect of restrike mode
Modulation of plasma properties.



Modulation of plasma properties



Synchronized ink-jet

Pulsed ink jet – Injection control

Microdispenser – On-demand injection
Triggering of injection following the arc voltage periods

Coatings deposition

Oxide formations
Nanostructured porous microstructures
in cauliflower shapes
Deposition efficiency improved with synchronisation

Growth mechanisms

